

# Design, Simulation and Fabrication of Plasmonic Pyramid Substrates for Cell Transfection

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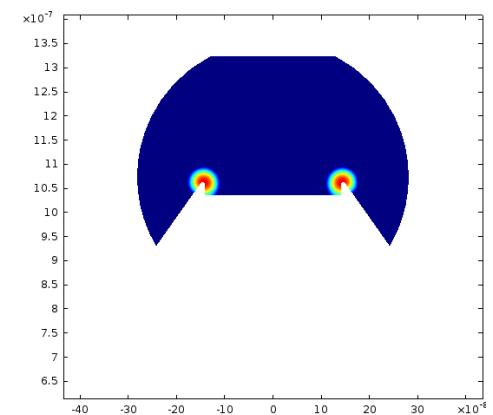
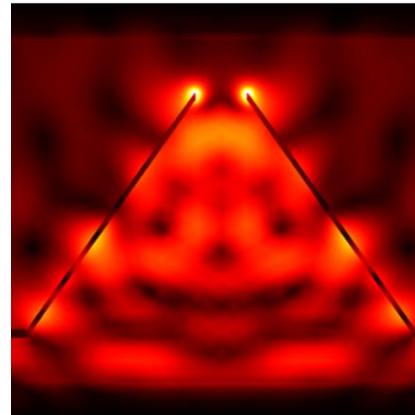
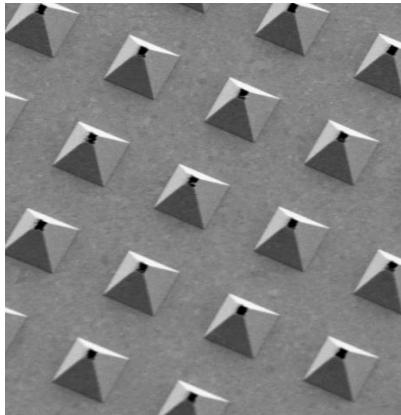
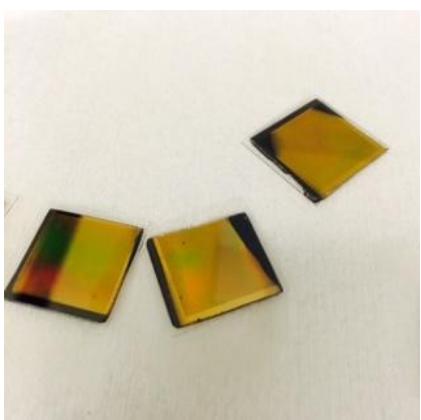
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<sup>2</sup>Univ. de Genève (Switzerland)

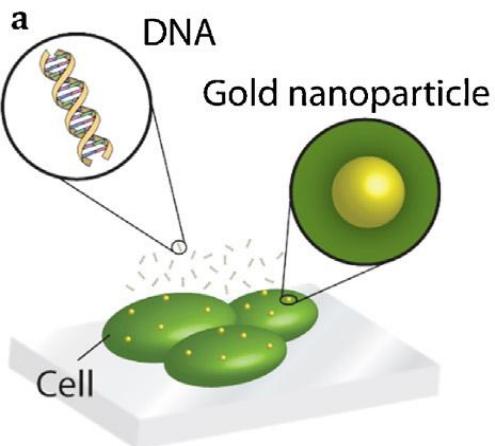
<sup>3</sup>Ludwig-Maximilians-Universität München (Germany)

<sup>4</sup>Massachusetts Institute of Technology (United States)

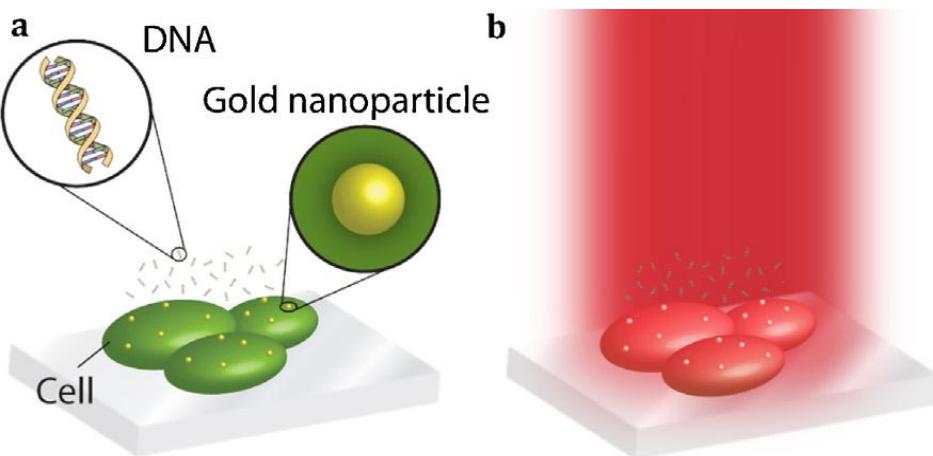
<sup>5</sup>École Polytechnique de Montréal



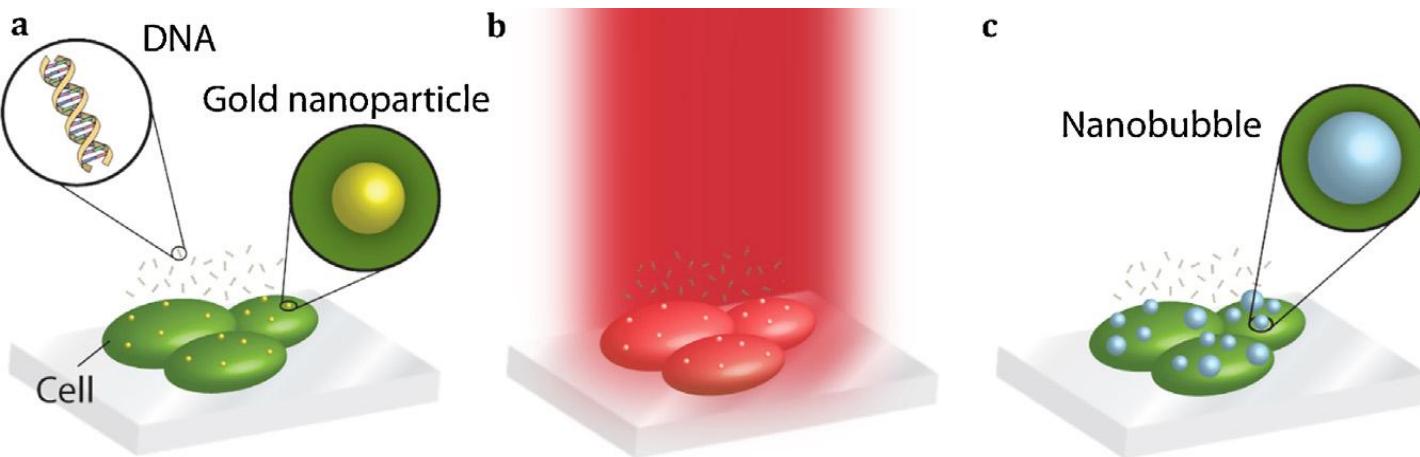
# Nanoparticles attach to the cell membrane



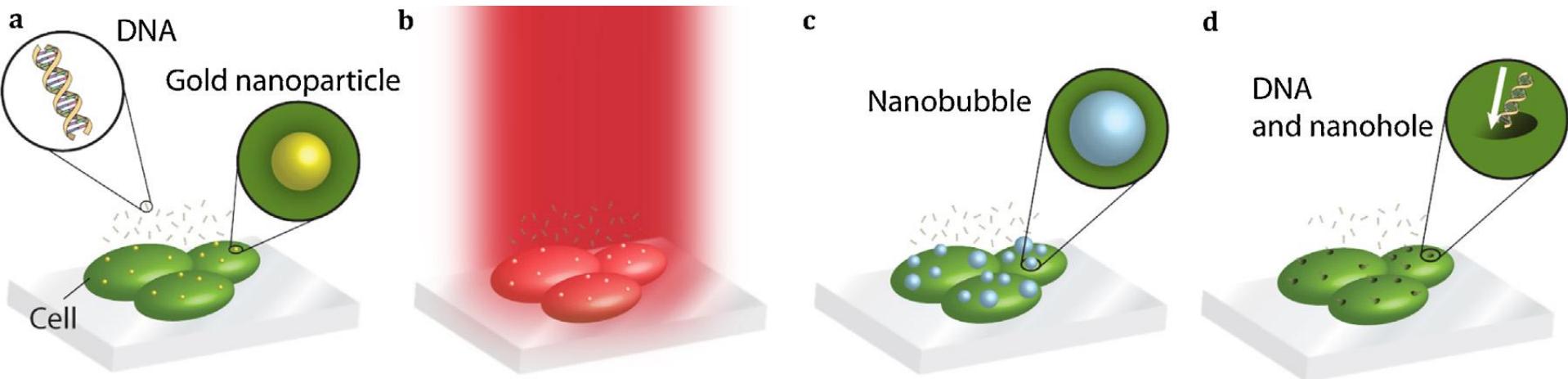
# Irradiating AuNPs near cells creates pores



# Irradiating AuNPs near cells creates pores



# External molecules can enter the cell



Plasmonics for pulsed-laser cell surgery: Fundamentals and applications *E. Boulais et al. Journal of Photochemistry and Photobiology C: Photochemistry Reviews* 2013

# External molecules can enter the cell



# External molecules can enter the cell

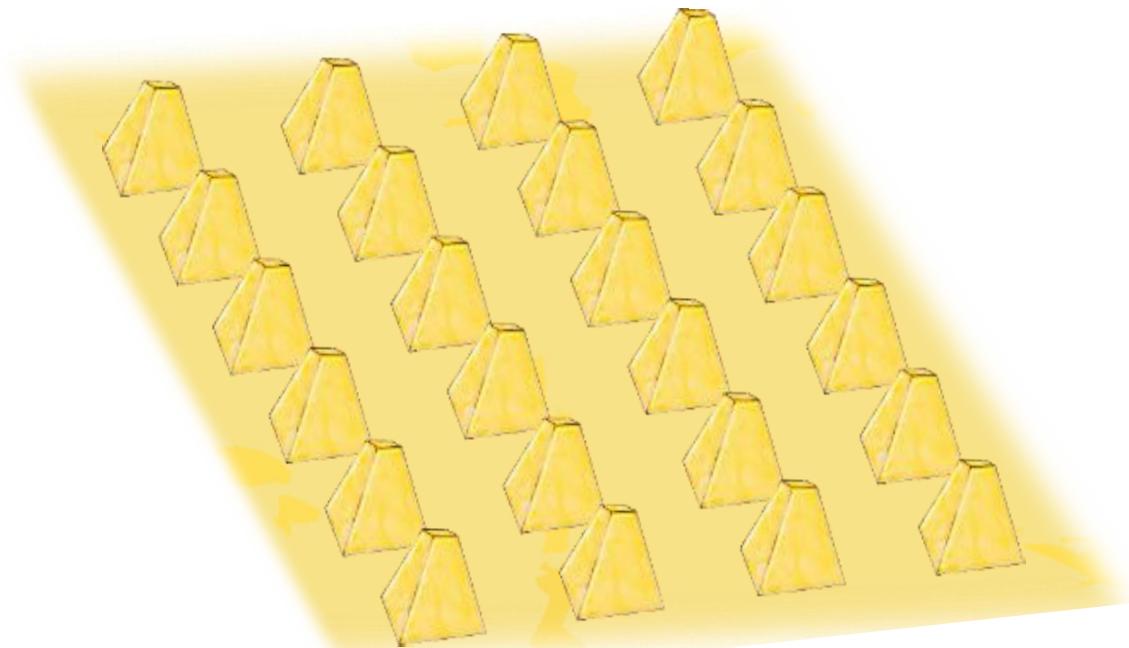


# Design aspects

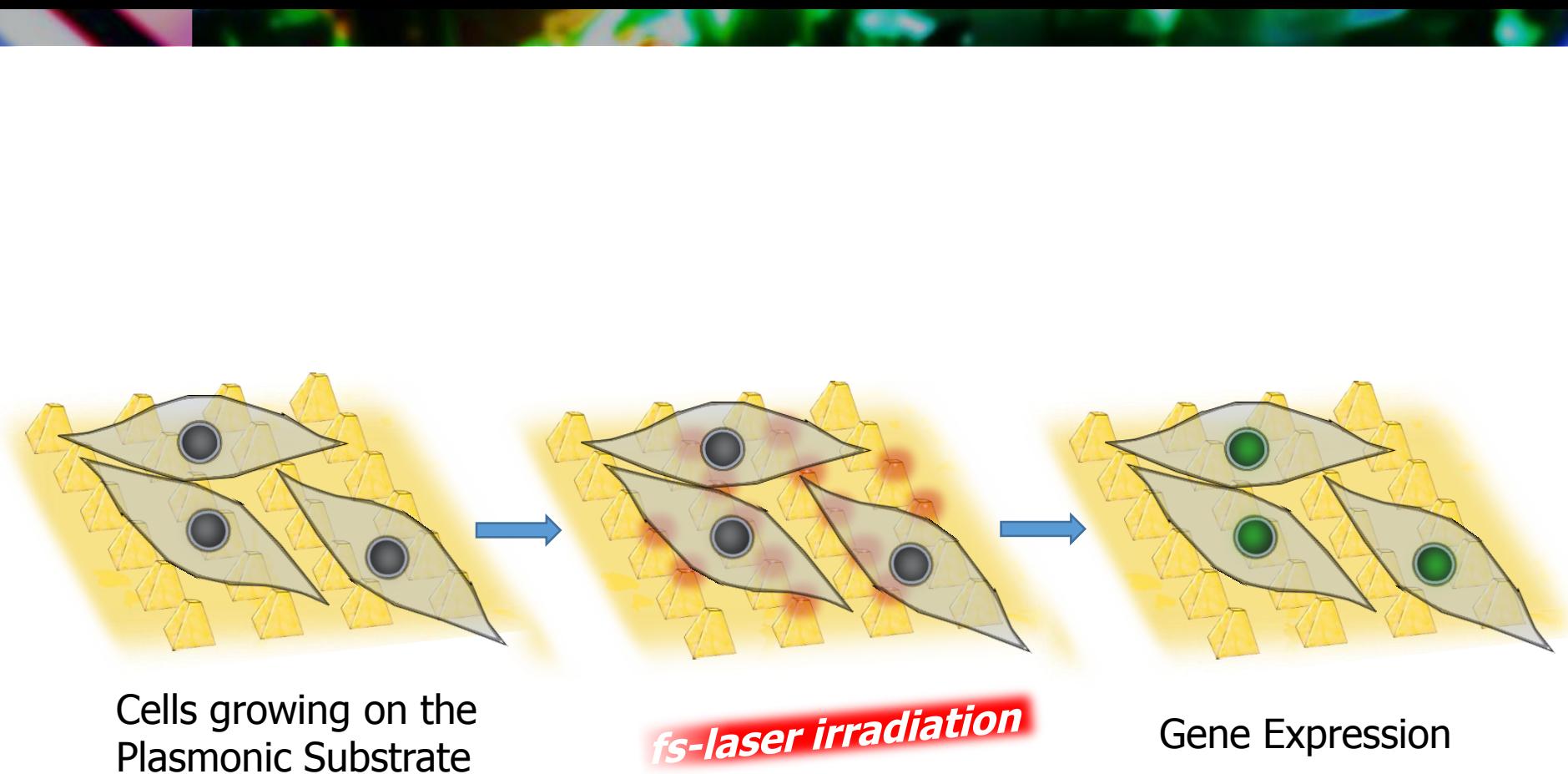
- 
1. Easy to Fabricate/Large-Scale-Fabrication
  2. Adjustable
  3. Strong Plasmonic Effect for Efficient and Localized Poration
  4. Robust/Stable

# Proposed structure

## Gold Pyramids with Nano-Apertures



# Experimental procedure



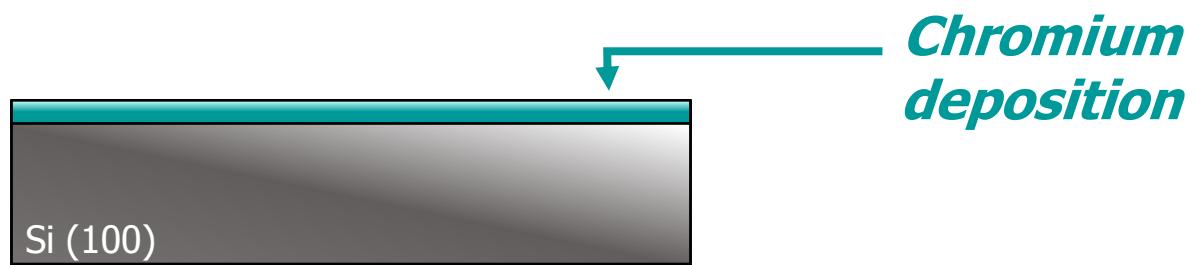
# Outline



Fabrication

Simulation and Characterization

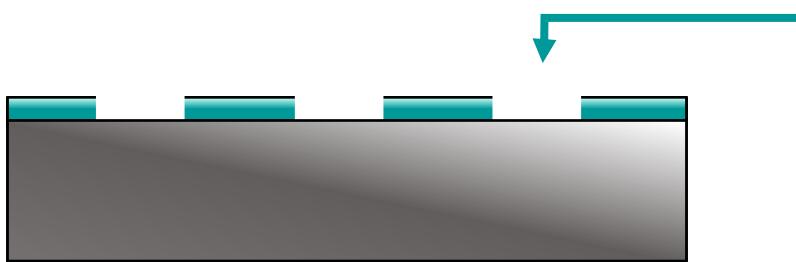
# Fabrication



# Fabrication



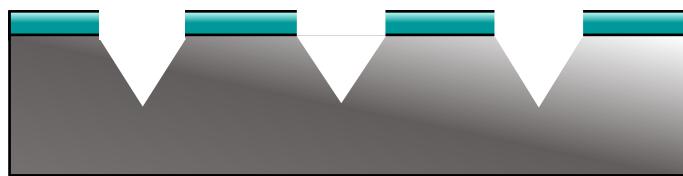
*E-Beam Lithography  
or  
Photolithography*



Negative squares  
of Cr thin films

# Fabrication

*KOH  
Anisotropic  
etching*



Inverted  
pyramids

# Fabrication

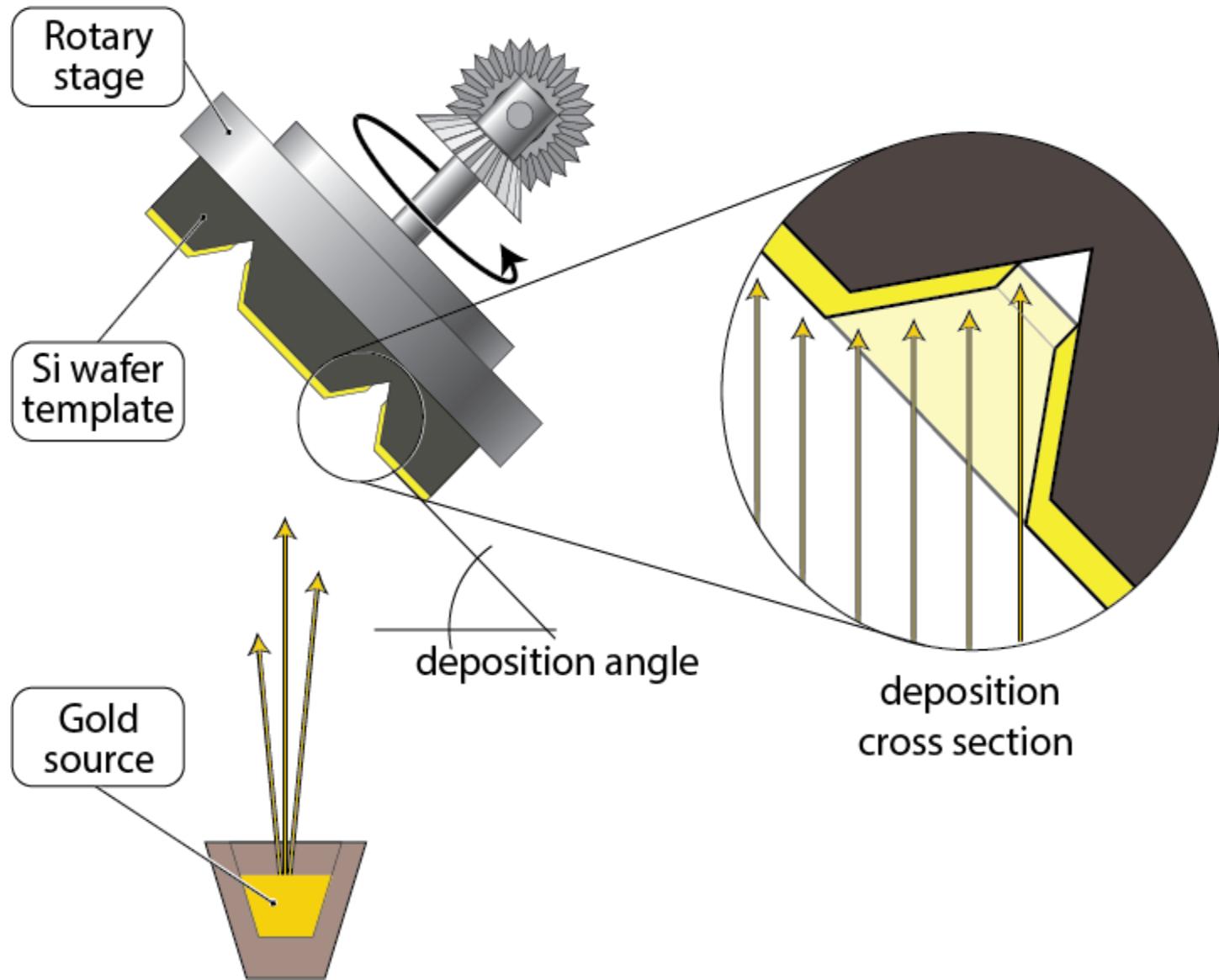


*Chromium etch*

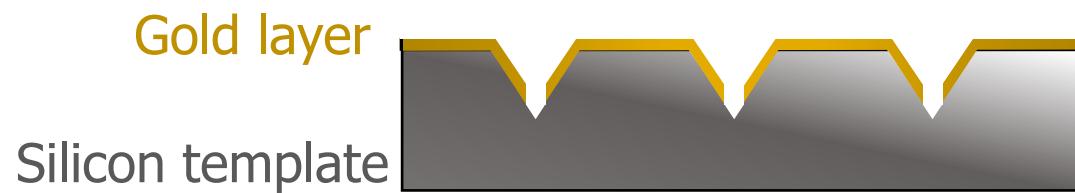


Template

# Fabrication

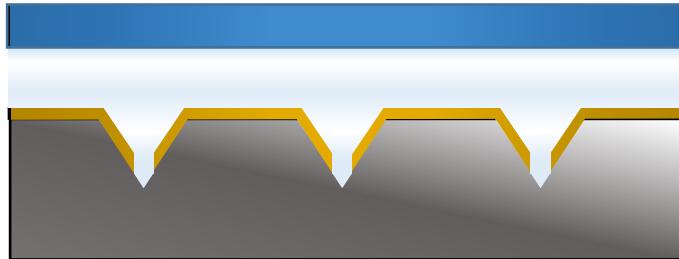


# Fabrication

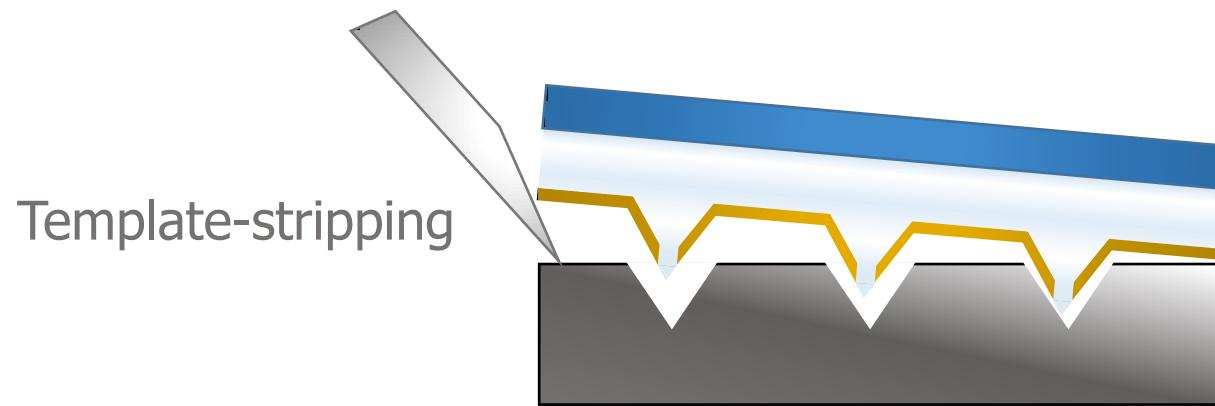


# Fabrication

Glass coverslip  
UV-cured glue

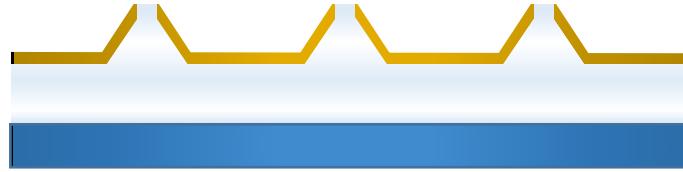


# Fabrication

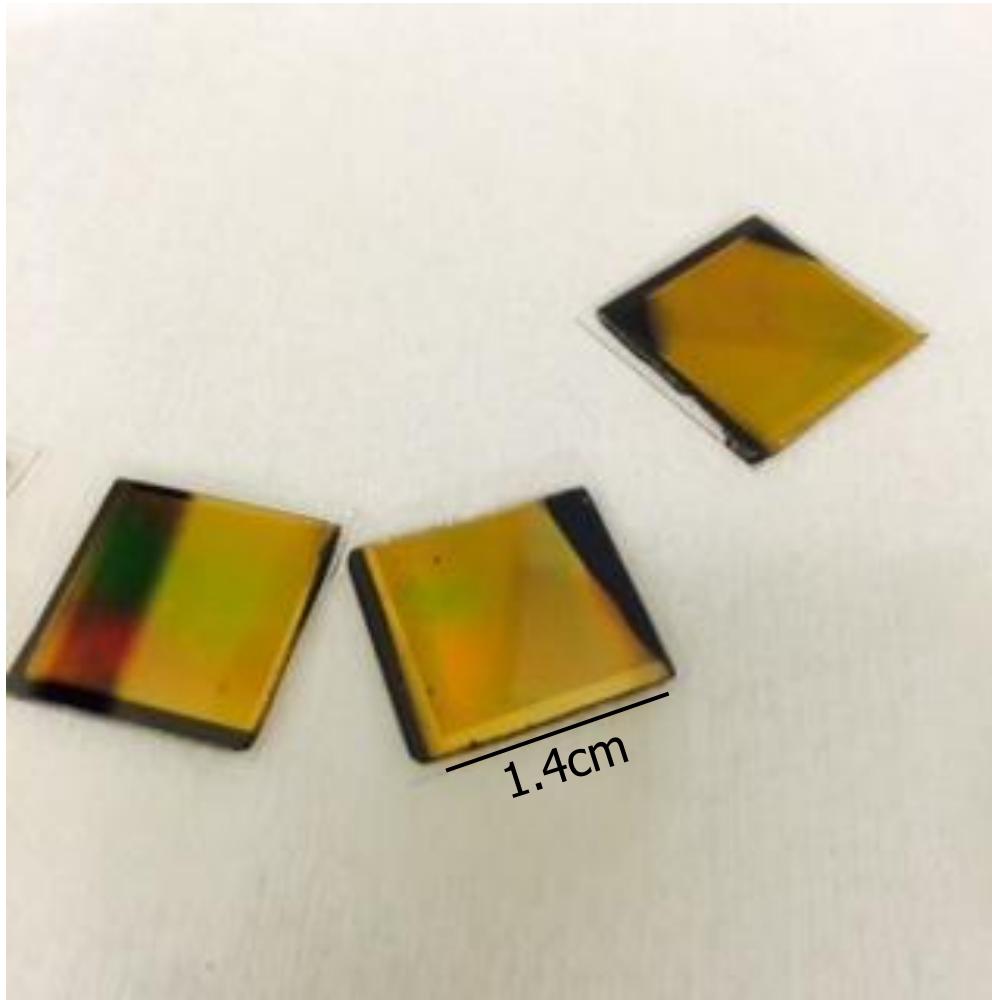


# Fabrication

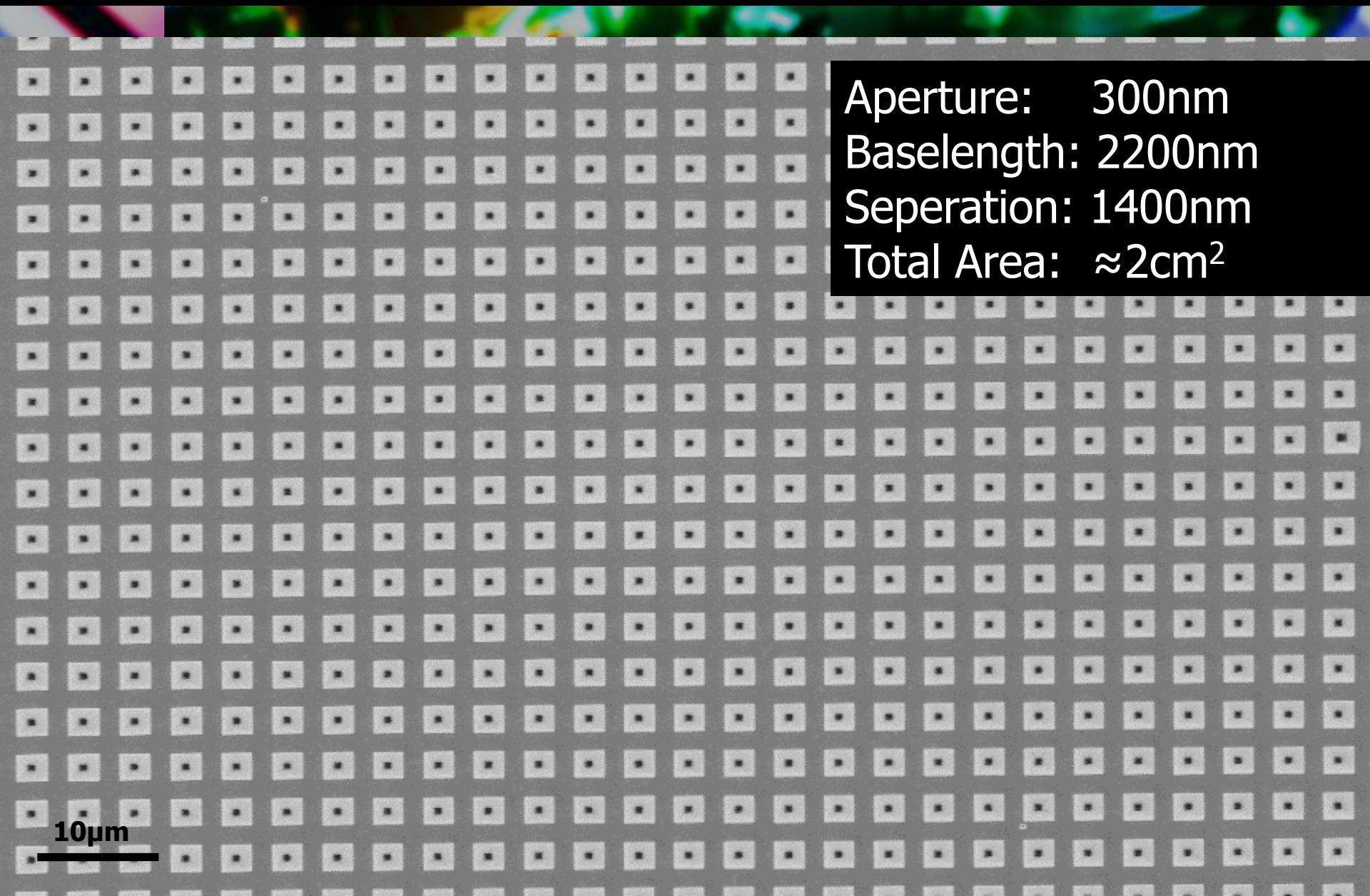
Tipless pyramids



# Fabricated substrates

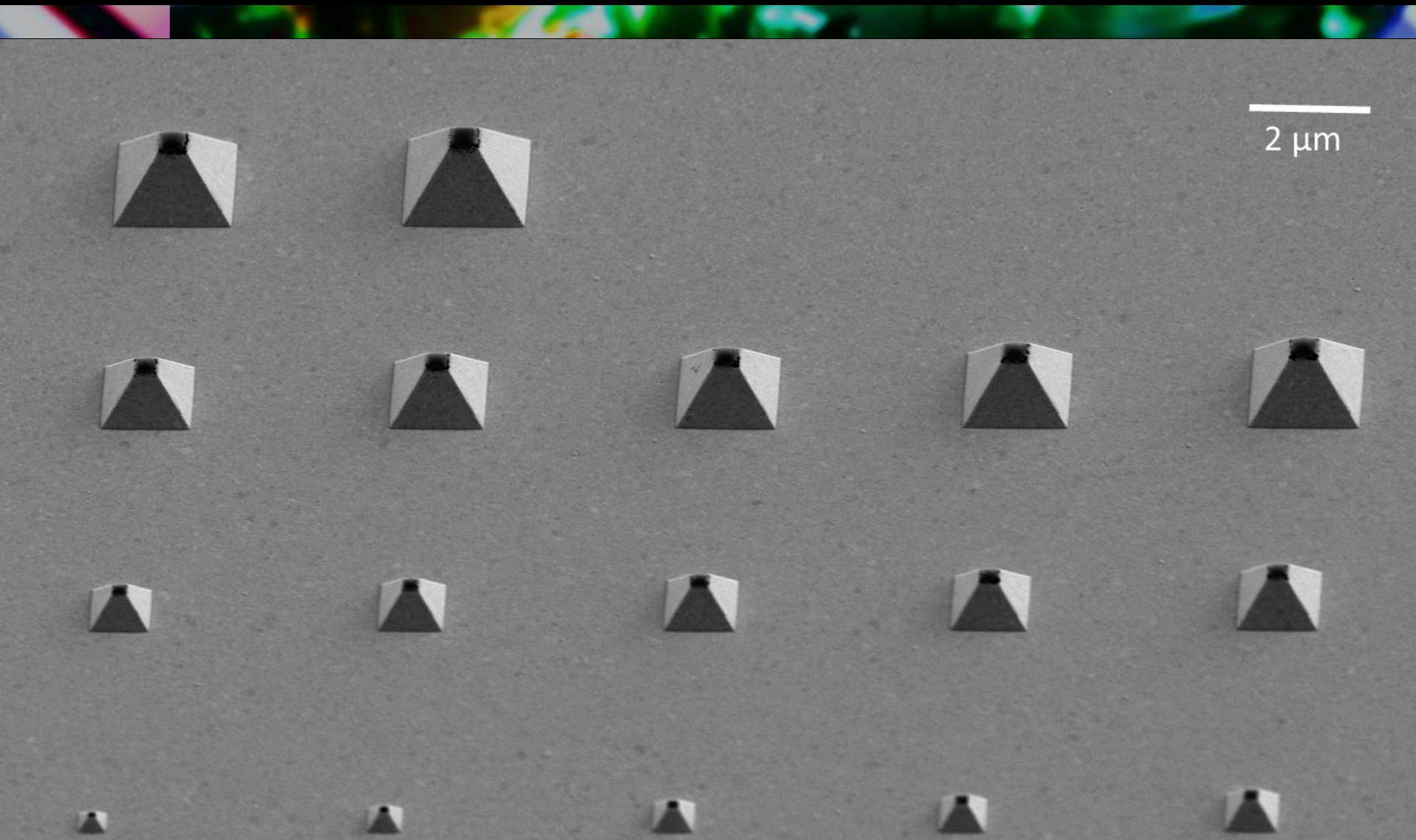


# Large-scale fabrication with photolithography



Aperture: 300nm  
Baselength: 2200nm  
Separation: 1400nm  
Total Area:  $\approx 2\text{cm}^2$

# Different aspect ratios



# Design aspects

- 
- 1. Easy to Fabricate/Large-Scale-Fabrication**
  - 2. Adjustable**
  - 3. Strong Plasmonic Effect for Efficient and Localized Poration**
  - 4. Robust/Stable**

# Outline

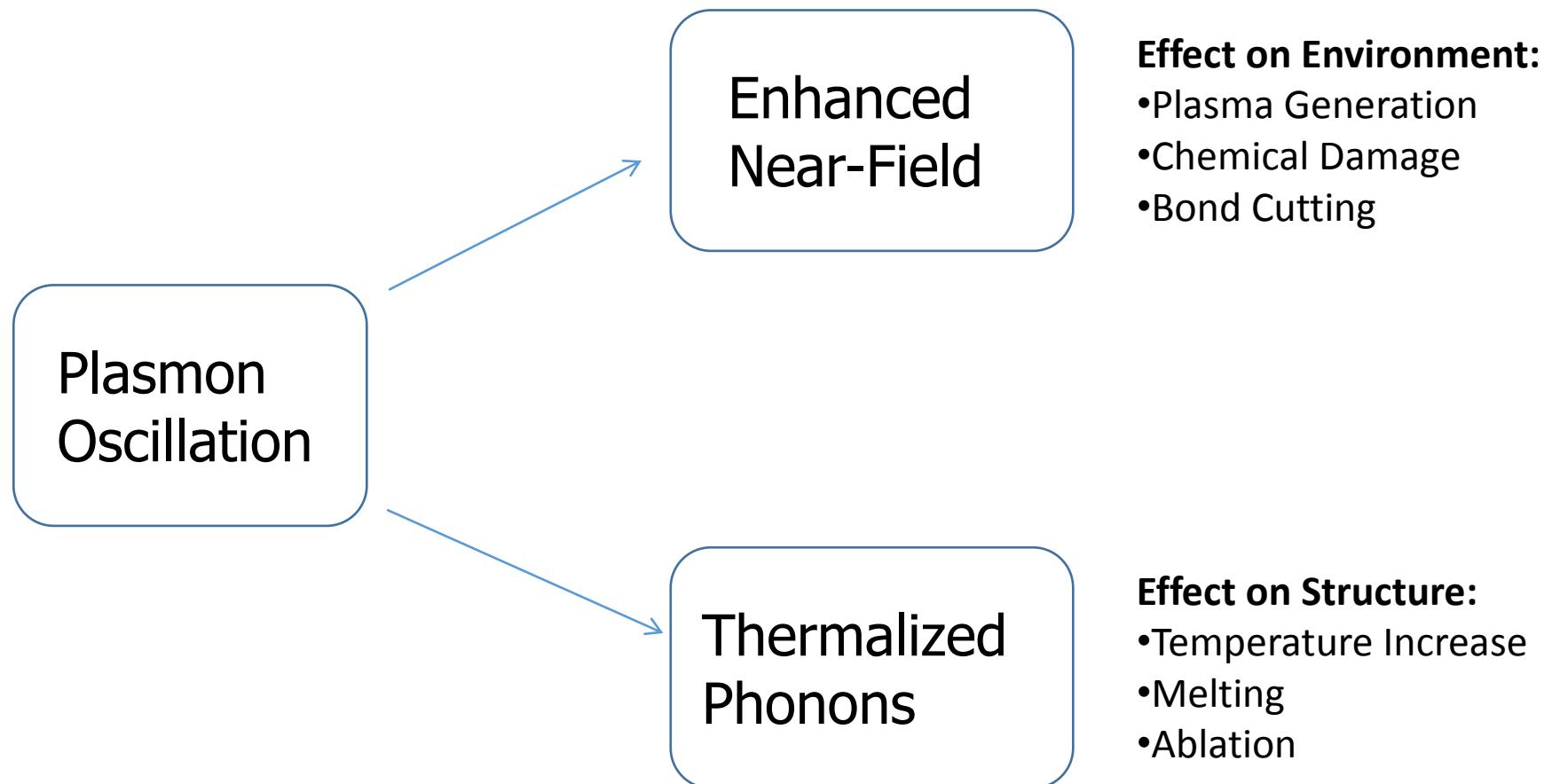


Fabrication

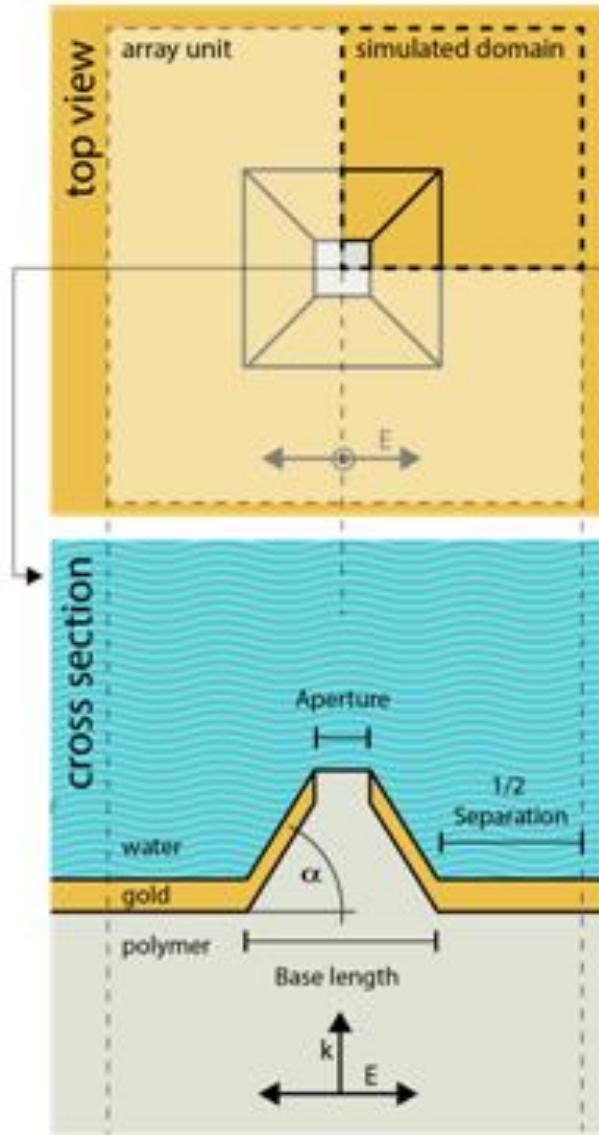


Simulation and Characterization

# Ultra-short laser excitation of plasmonic structures



# Simulations: Field Enhancement

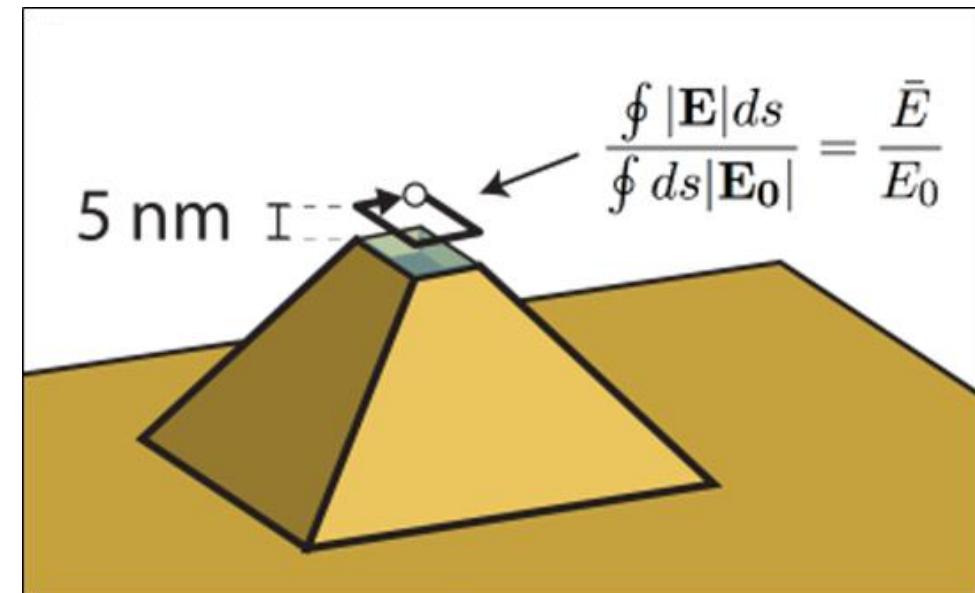


Optimization for 800nm excitation

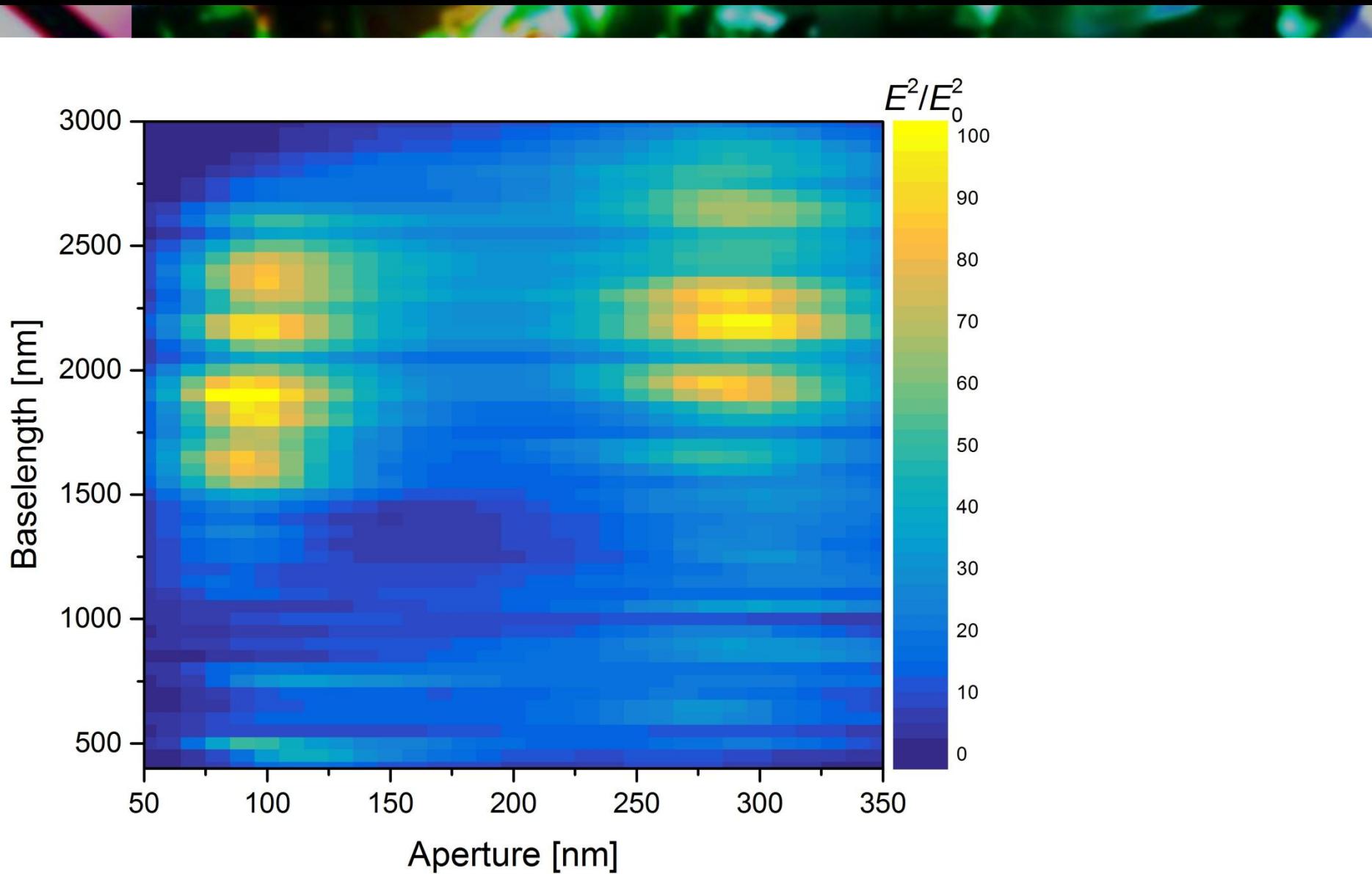
Geometrical Parameters to Explore:

- Baselength
- Aperture
- Separation

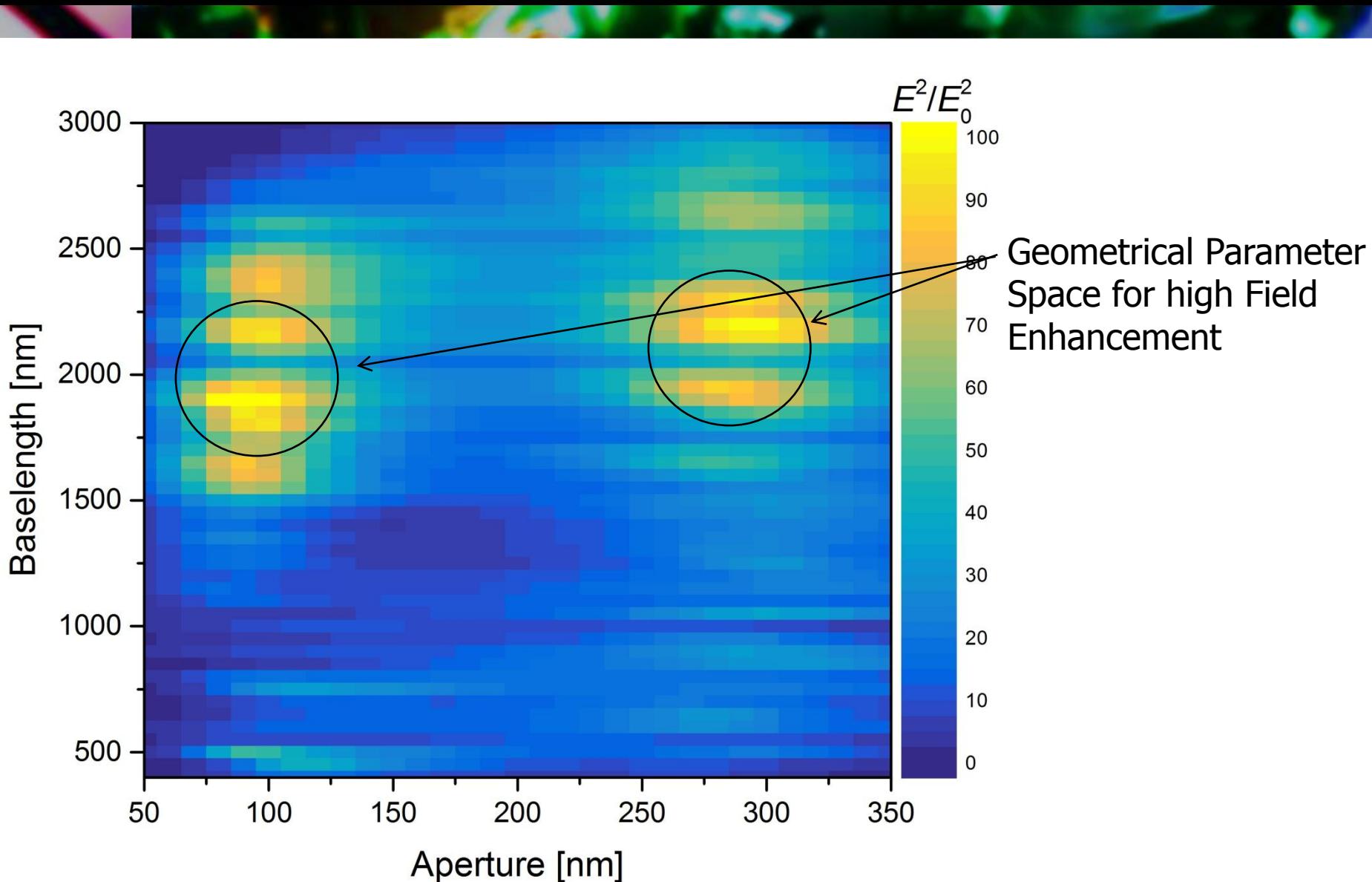
Figure of Merit:  
Average Field Enhancement  
5nm above the Aperture



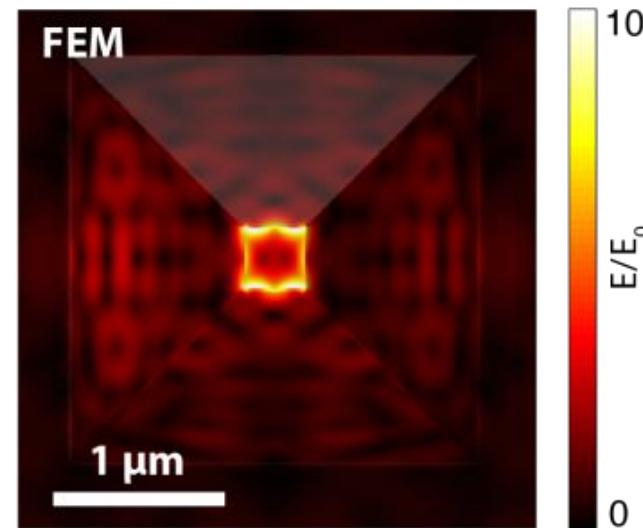
# Optimization: Field Enhancement



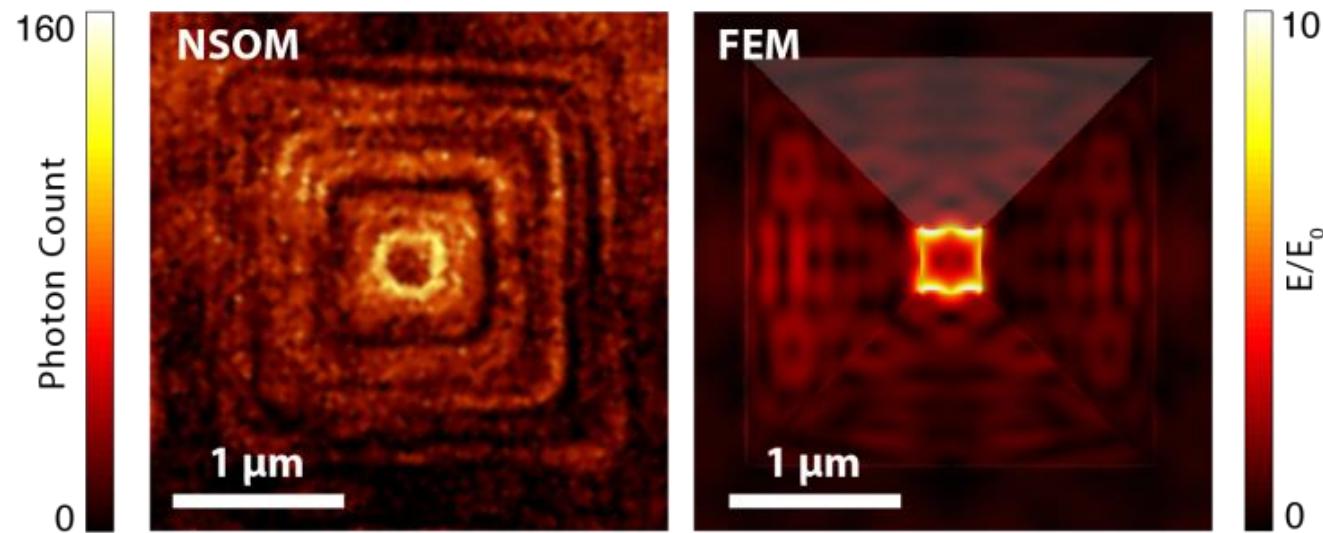
# Optimization: Field Enhancement



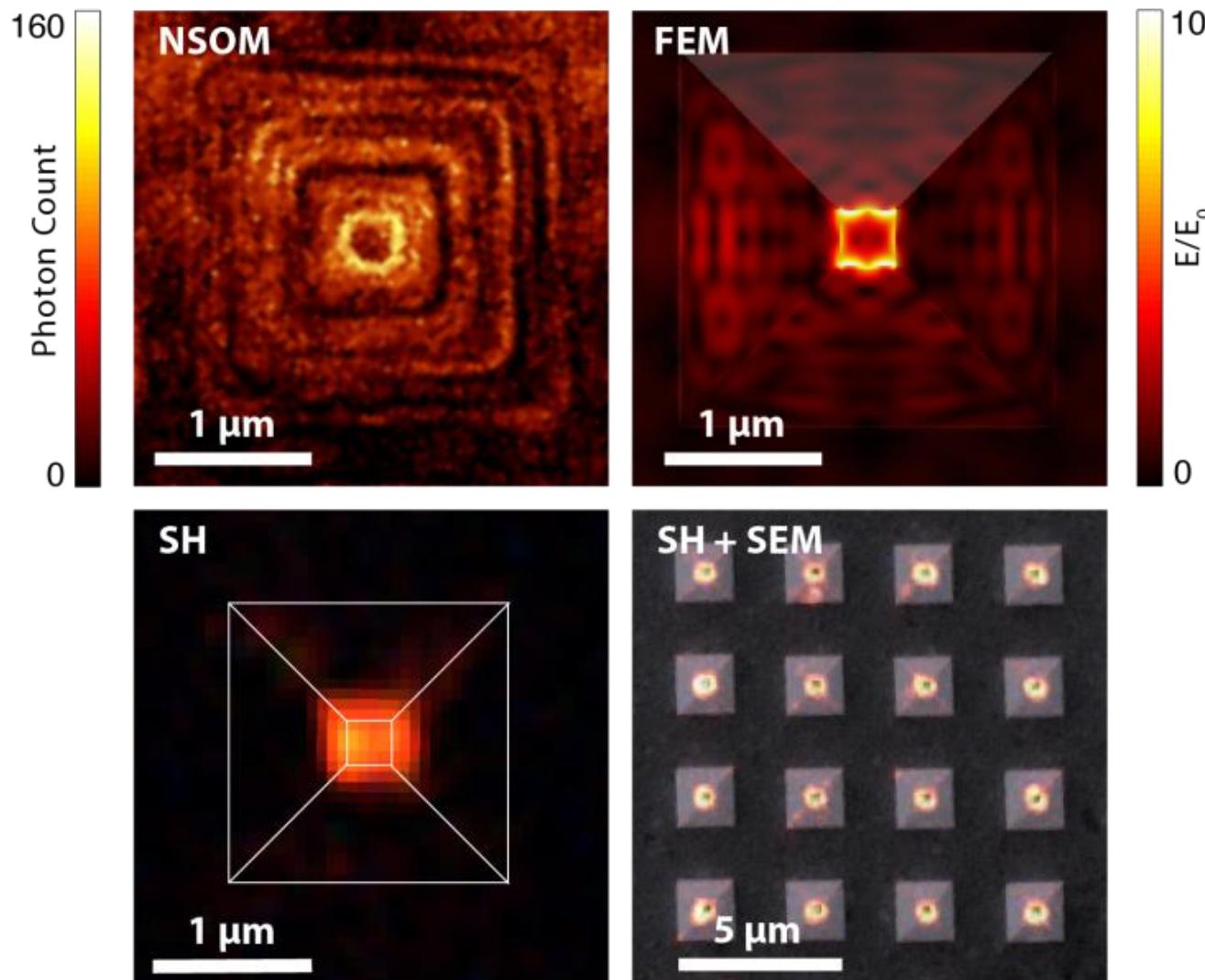
# Experiments vs Simulation



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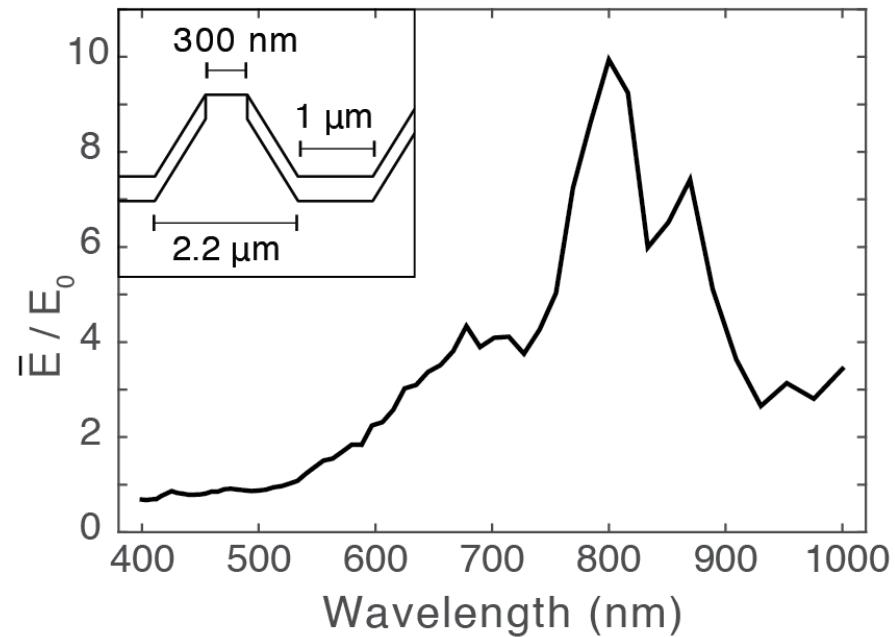
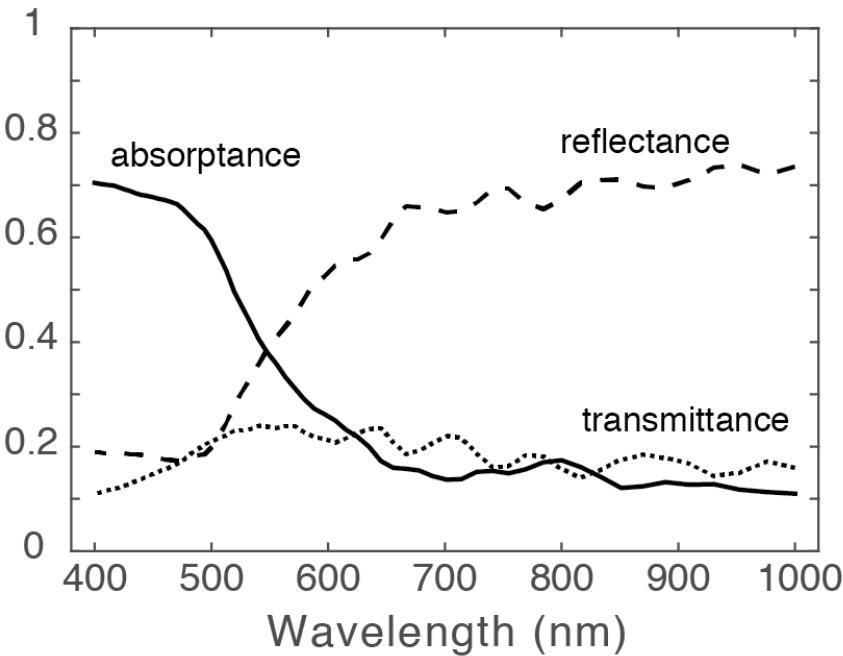


# Experiments vs Simulation

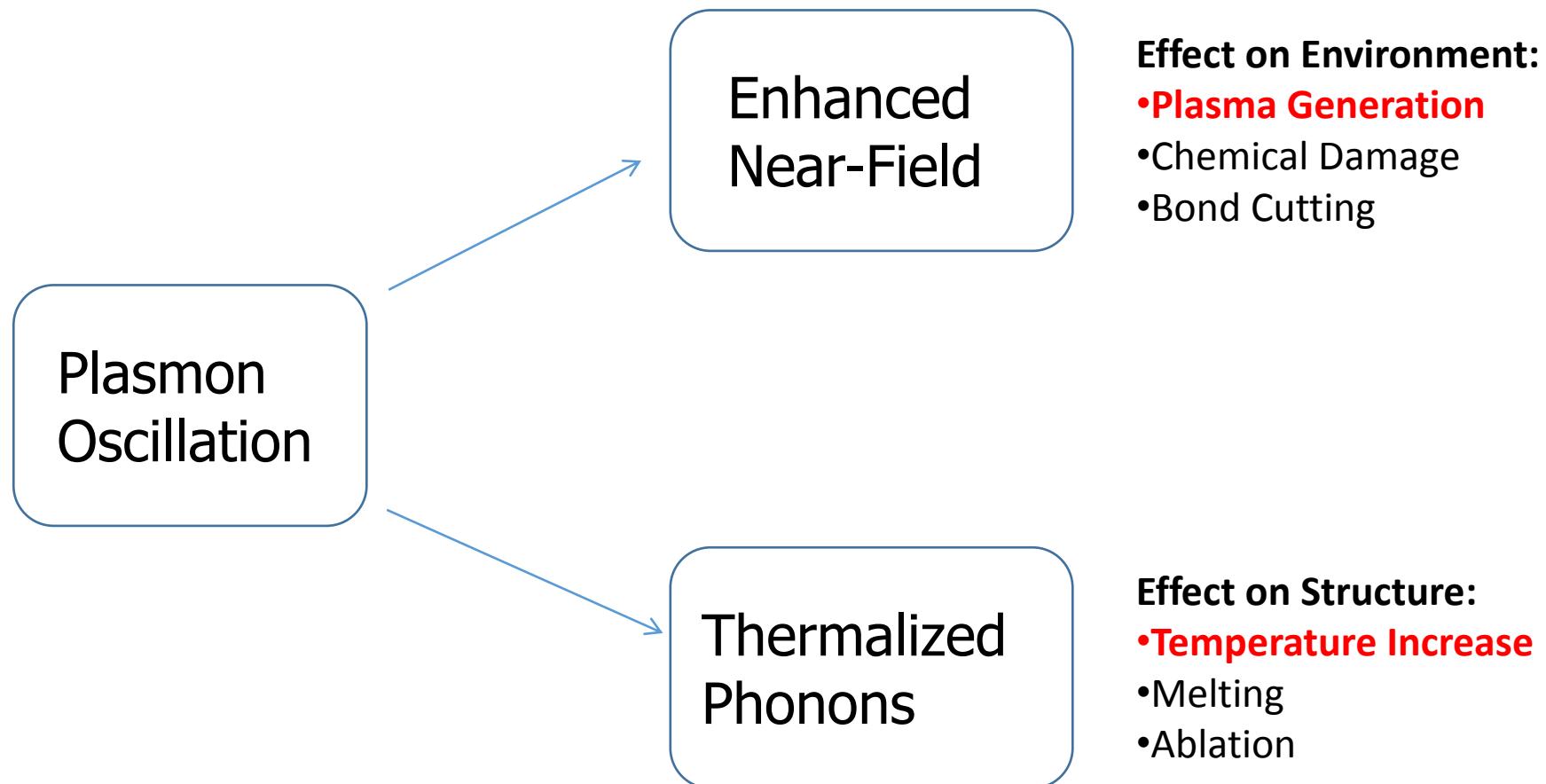


# Simulations: Field Enhancement

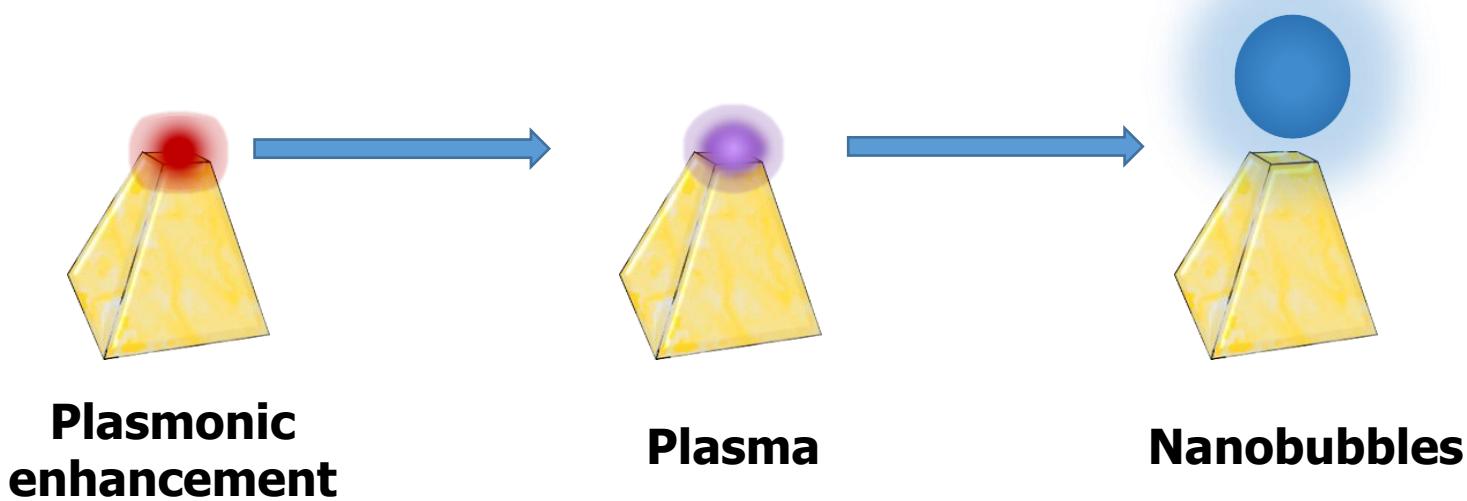
Low-absorptance regime to avoid thermal damage of the structure



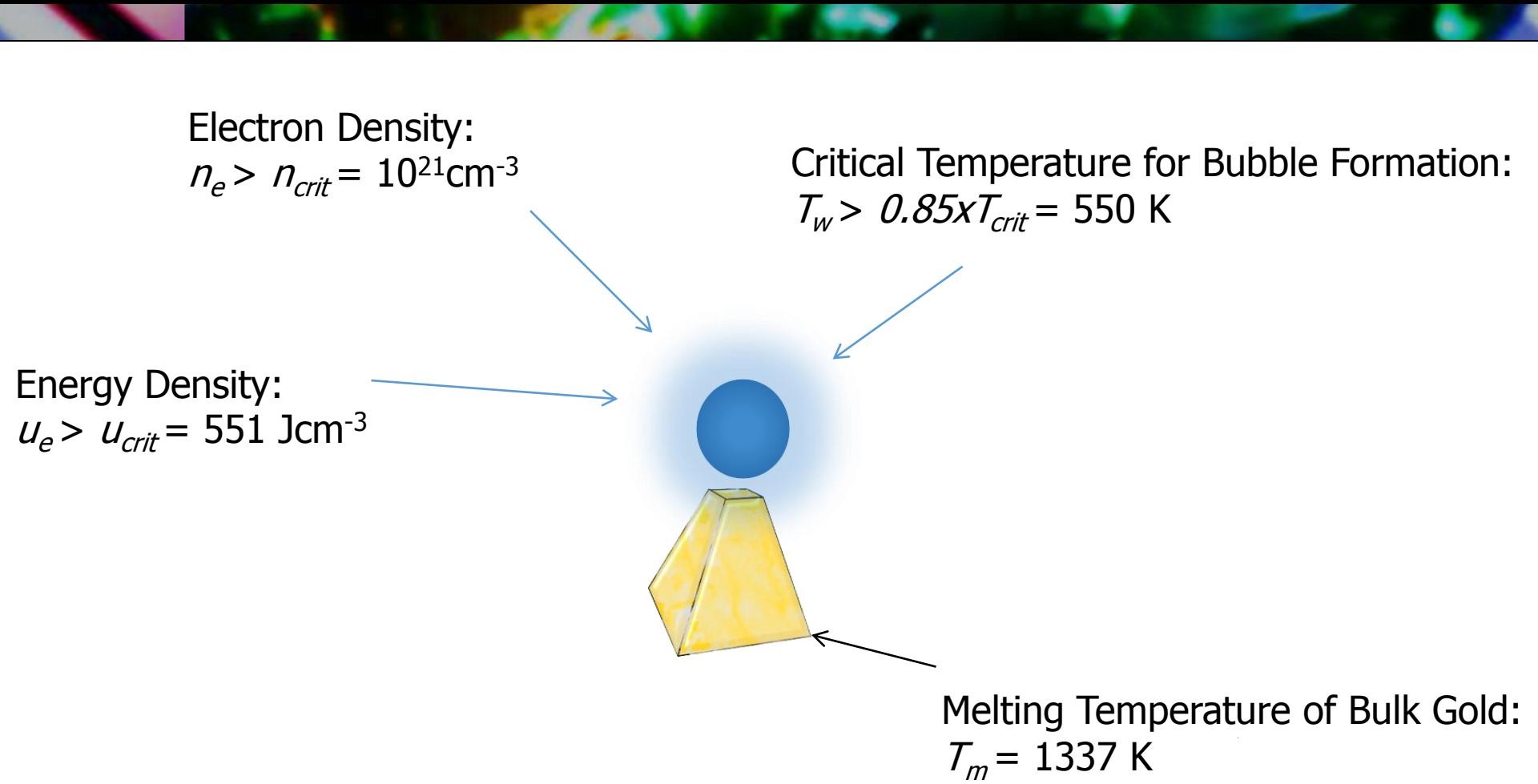
# Ultra-short laser excitation of plasmonic structures



# Plasma-mediated bubble formation



# Plasma-mediated bubble formation



Mechanisms of femtosecond laser nanosurgery of cells and tissues Vogel et al. Appl. Phys. B: Lasers Opt. 81 (2005) 1015–1047.

Plasmonics for pulsed-laser cell surgery: Fundamentals and applications E. Boulais et al. Journal of Photochemistry and Photobiology C: Photochemistry Reviews 2013

# Plasma Formation



Wavelength: 800nm

Pulse length: 100fs

Fluence: 10mJ/cm<sup>2</sup>

Baselength: 1800nm

Aperture: 300nm

Gold Layer: 50nm

# Plasma Formation



Wavelength: 800nm

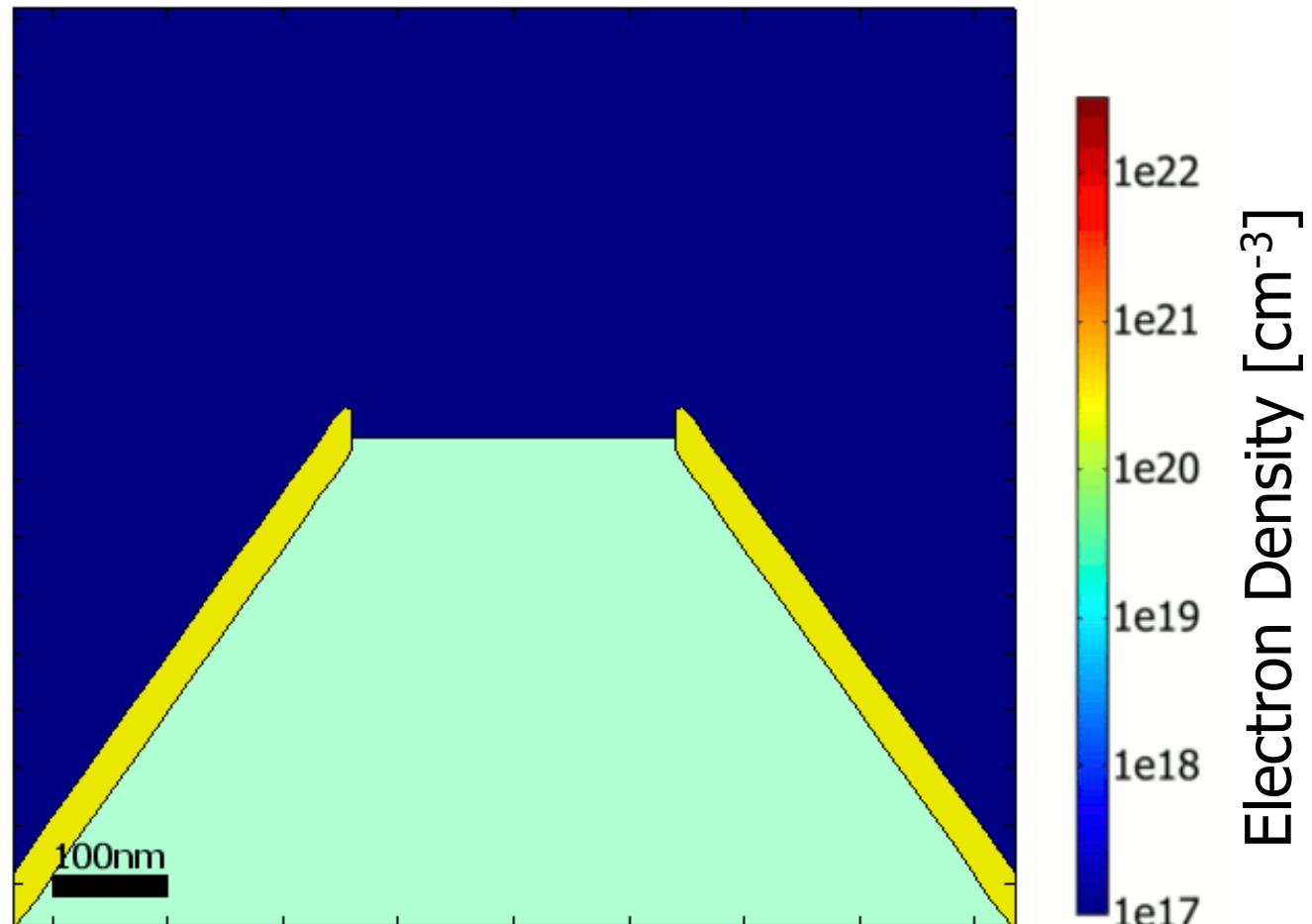
Pulse length: 100fs

Fluence: 10mJ/cm<sup>2</sup>

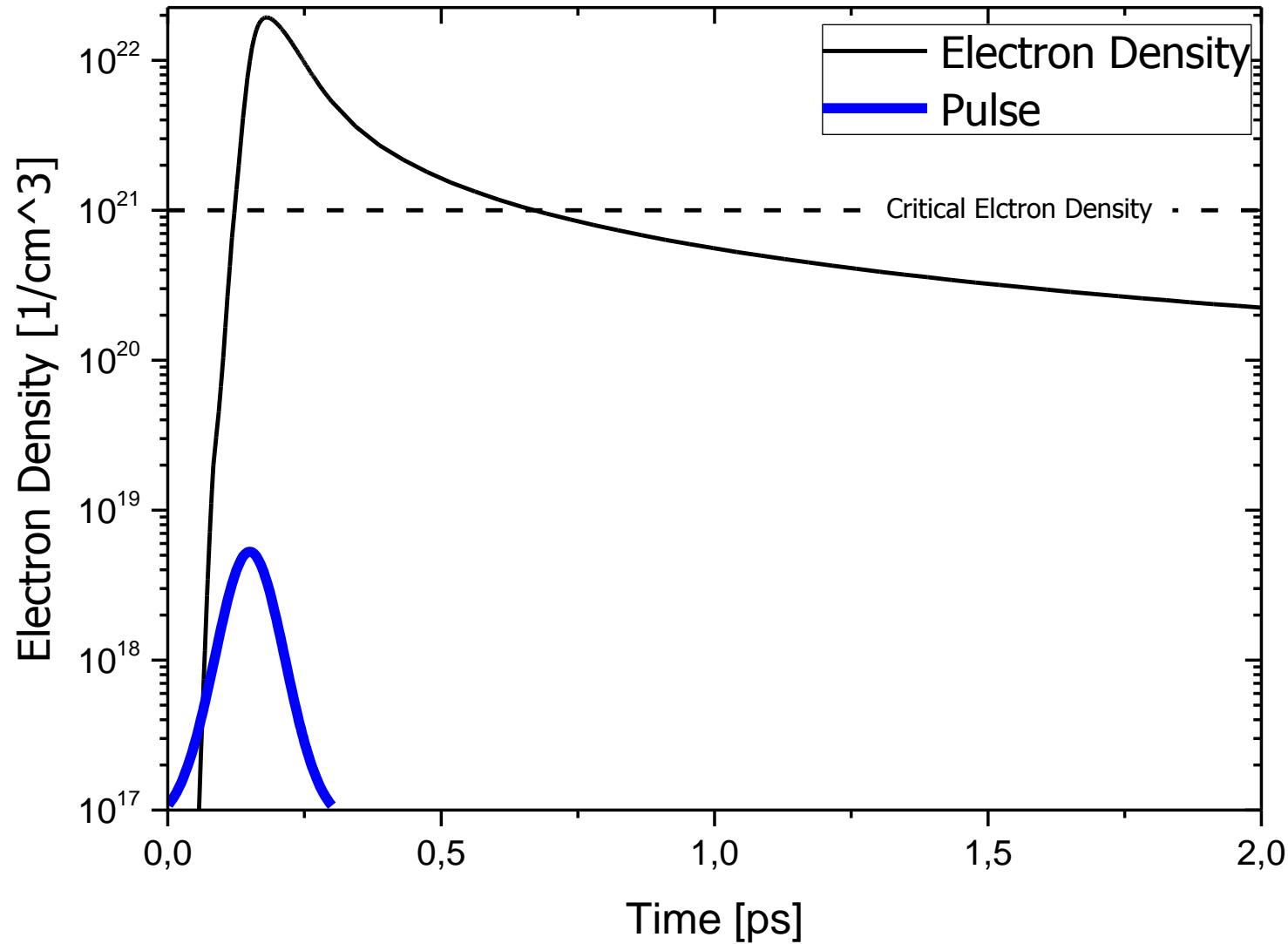
Baselength: 1800nm

Aperture: 300nm

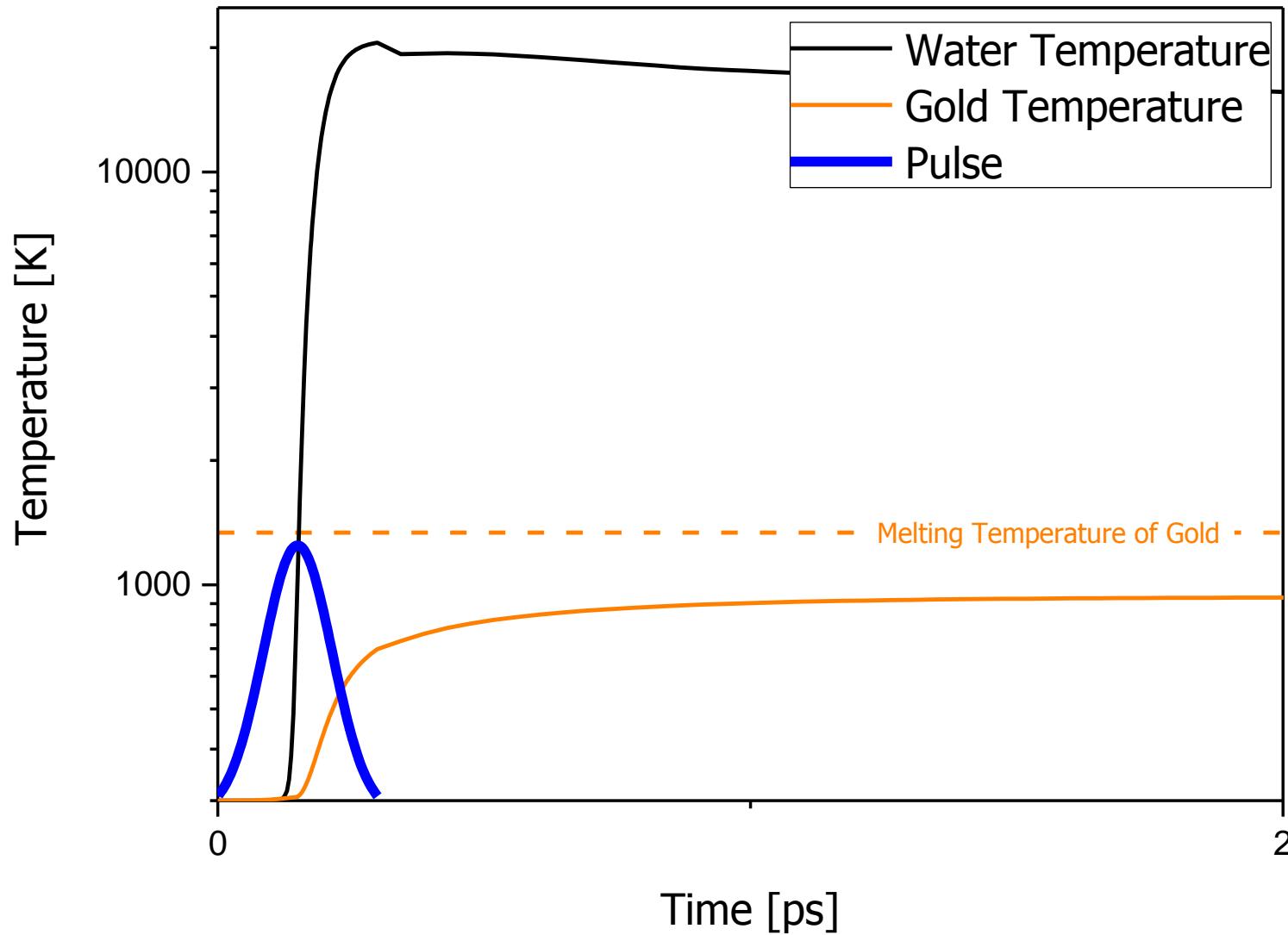
Gold Layer: 50nm



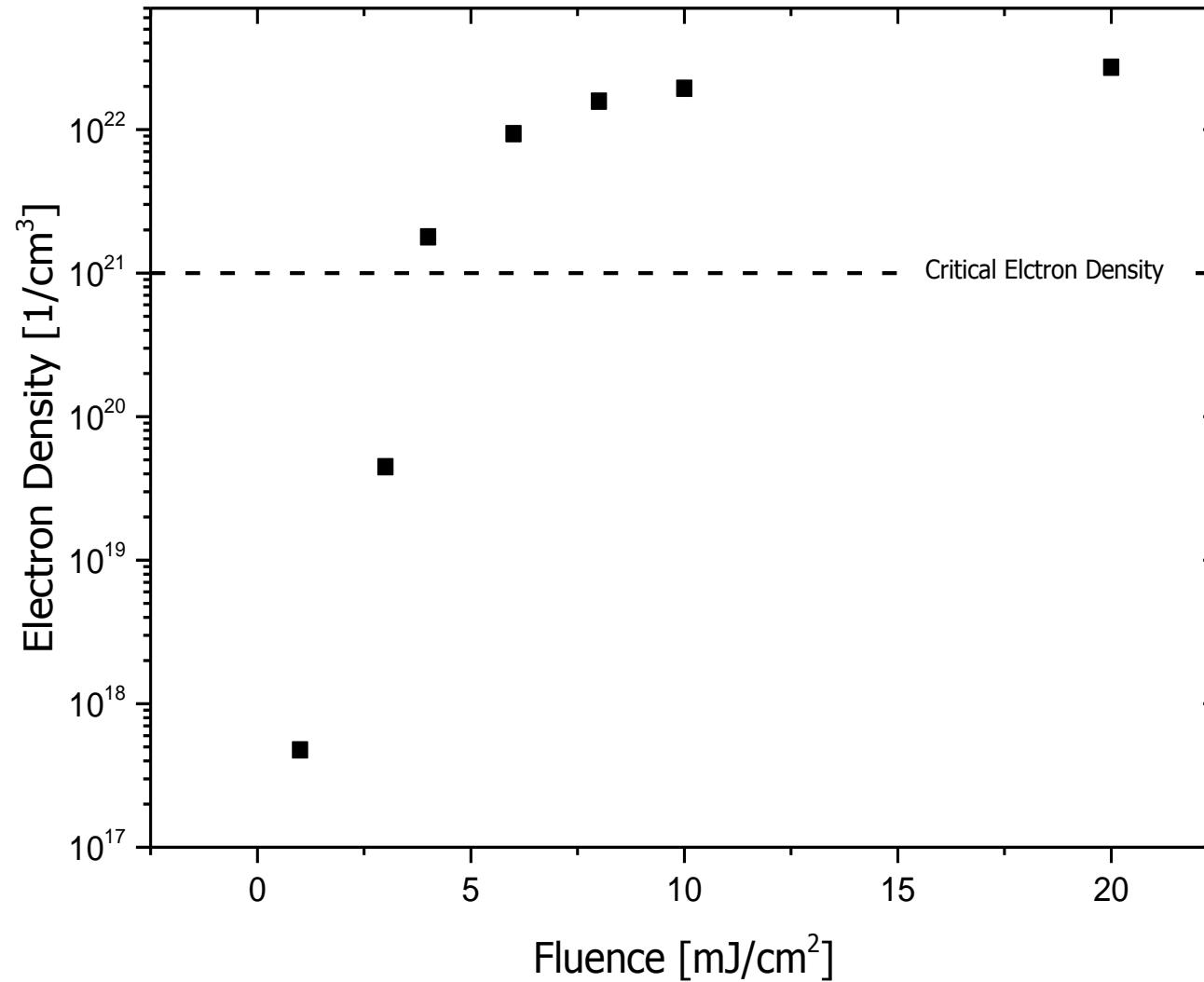
# Plasma Formation



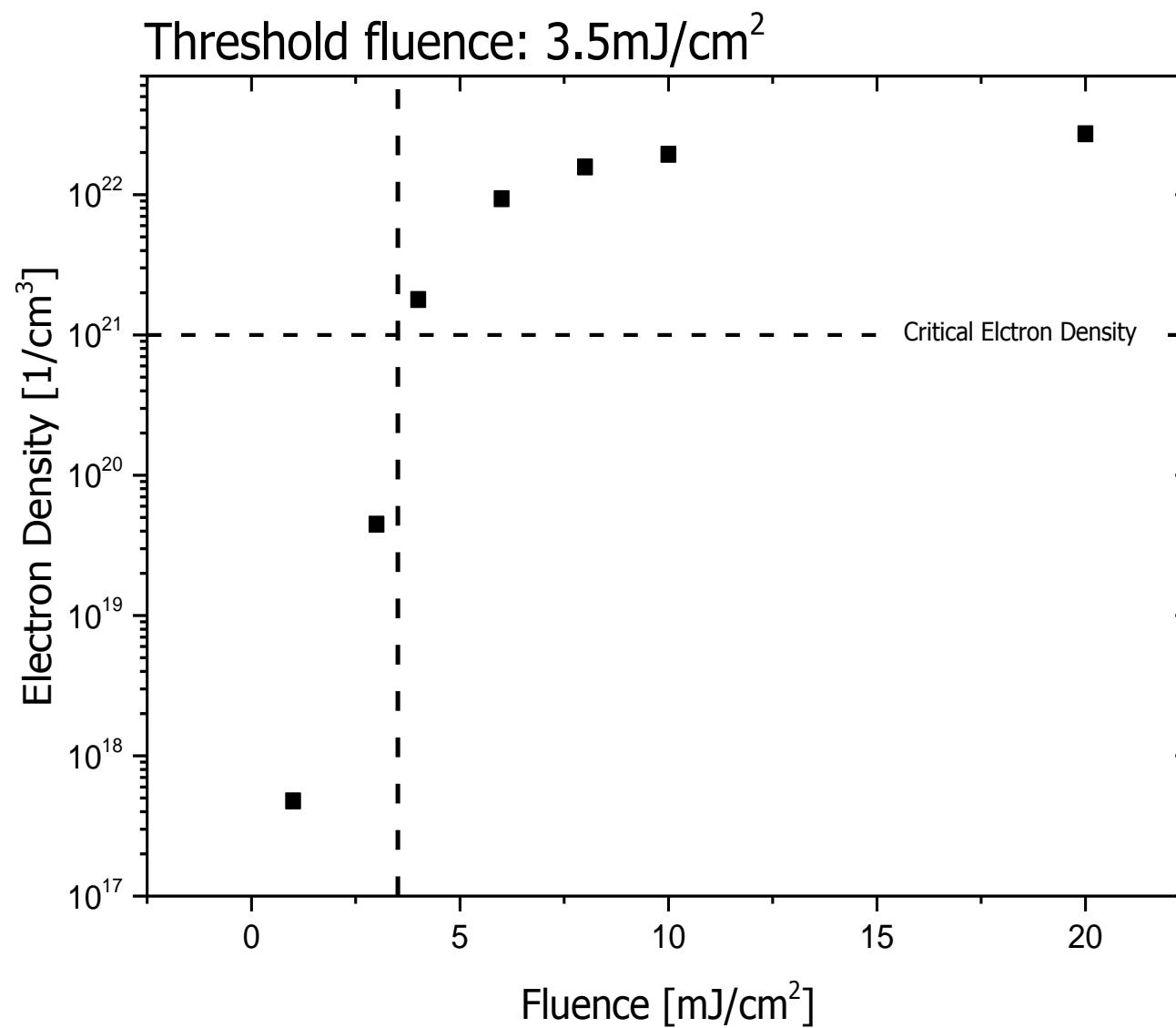
# Plasma Formation



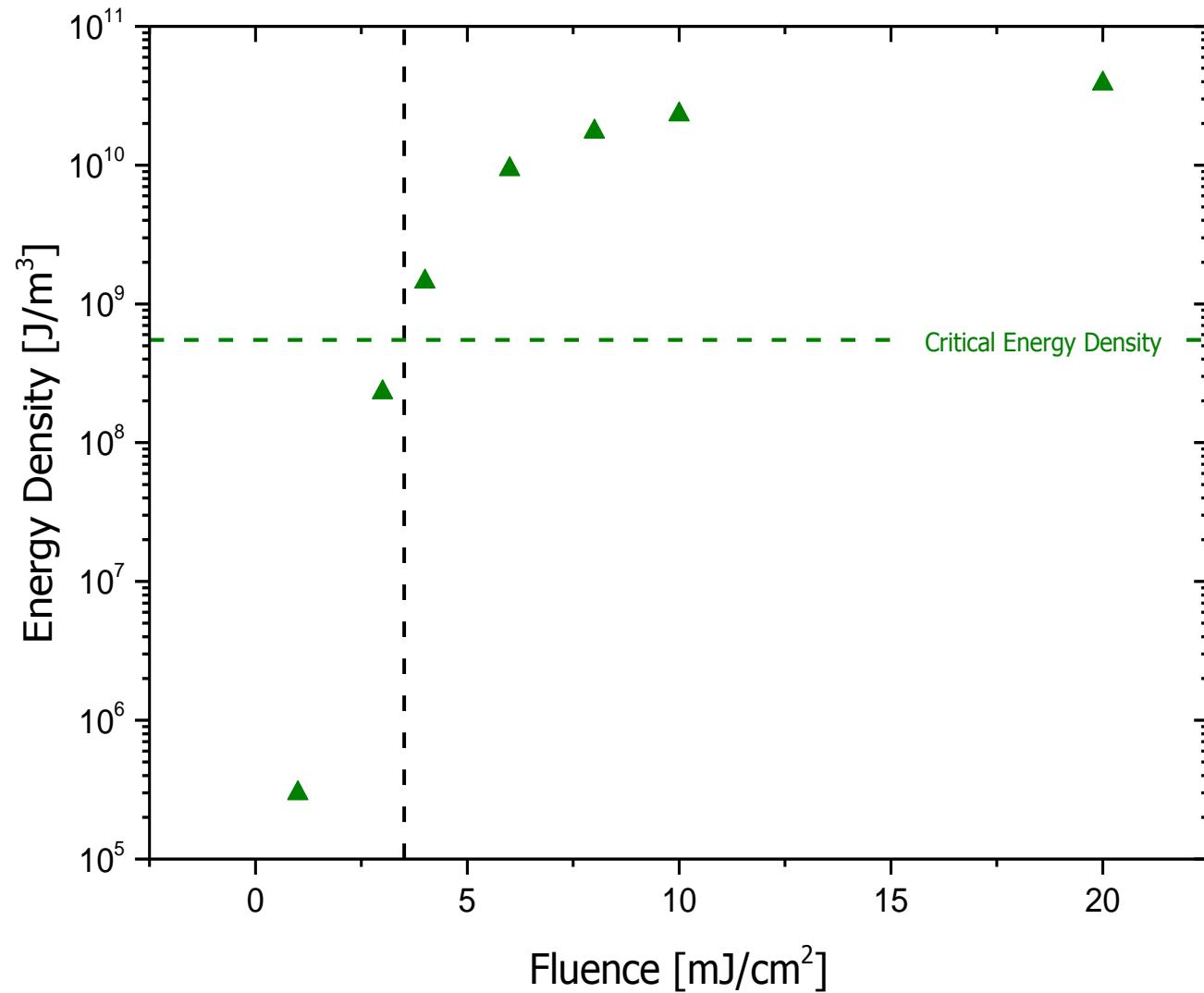
# Plasma Formation



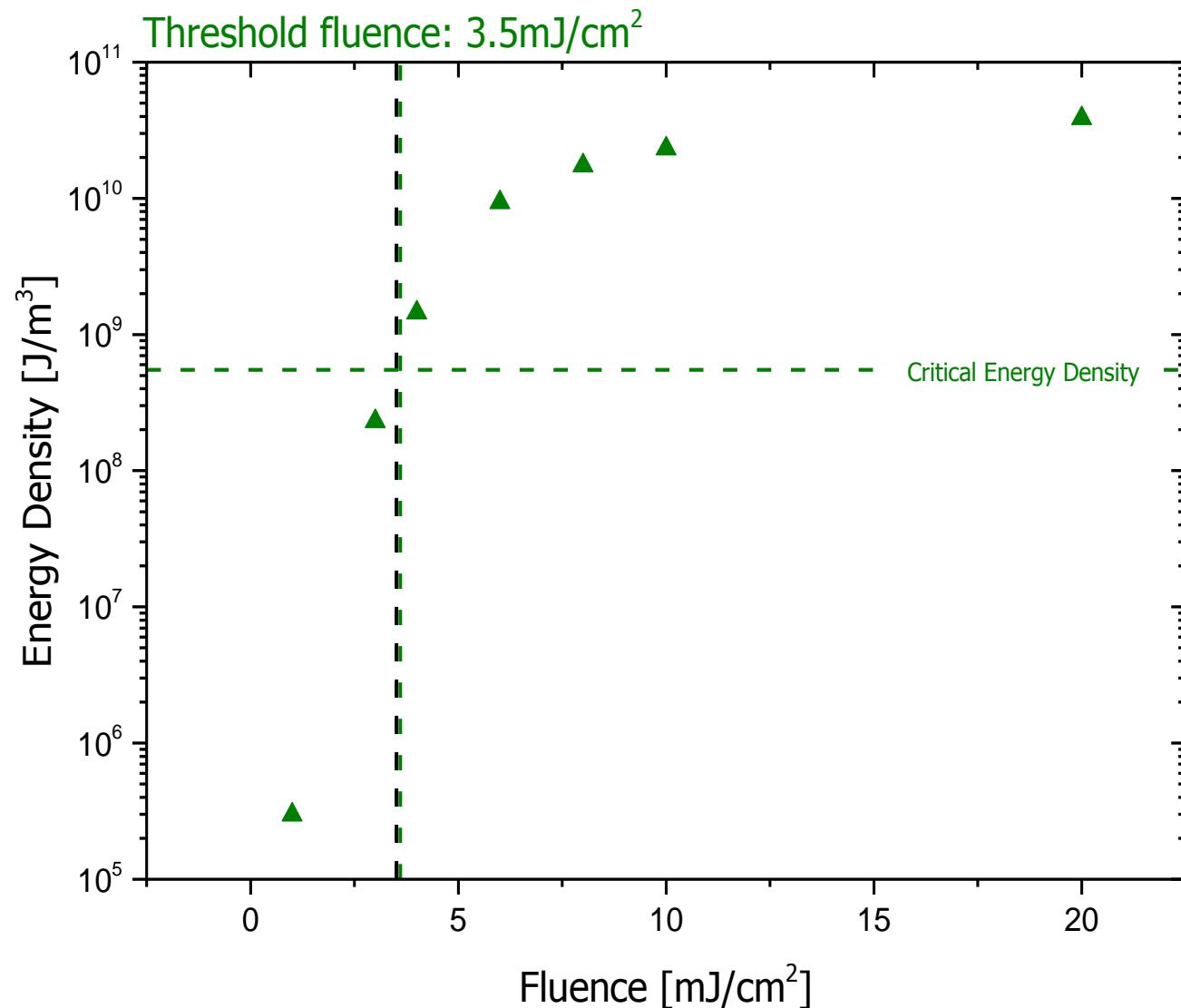
# Plasma Formation



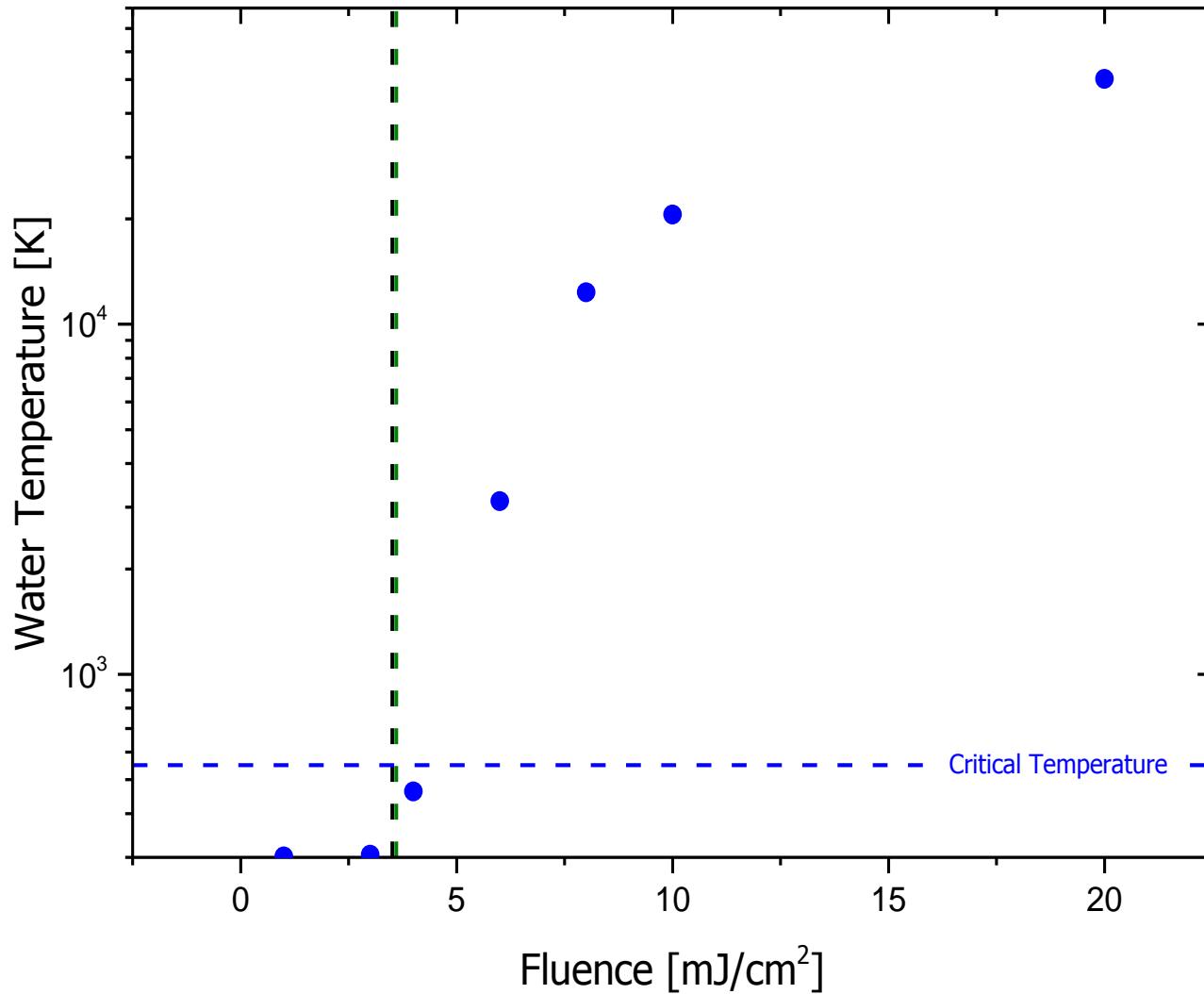
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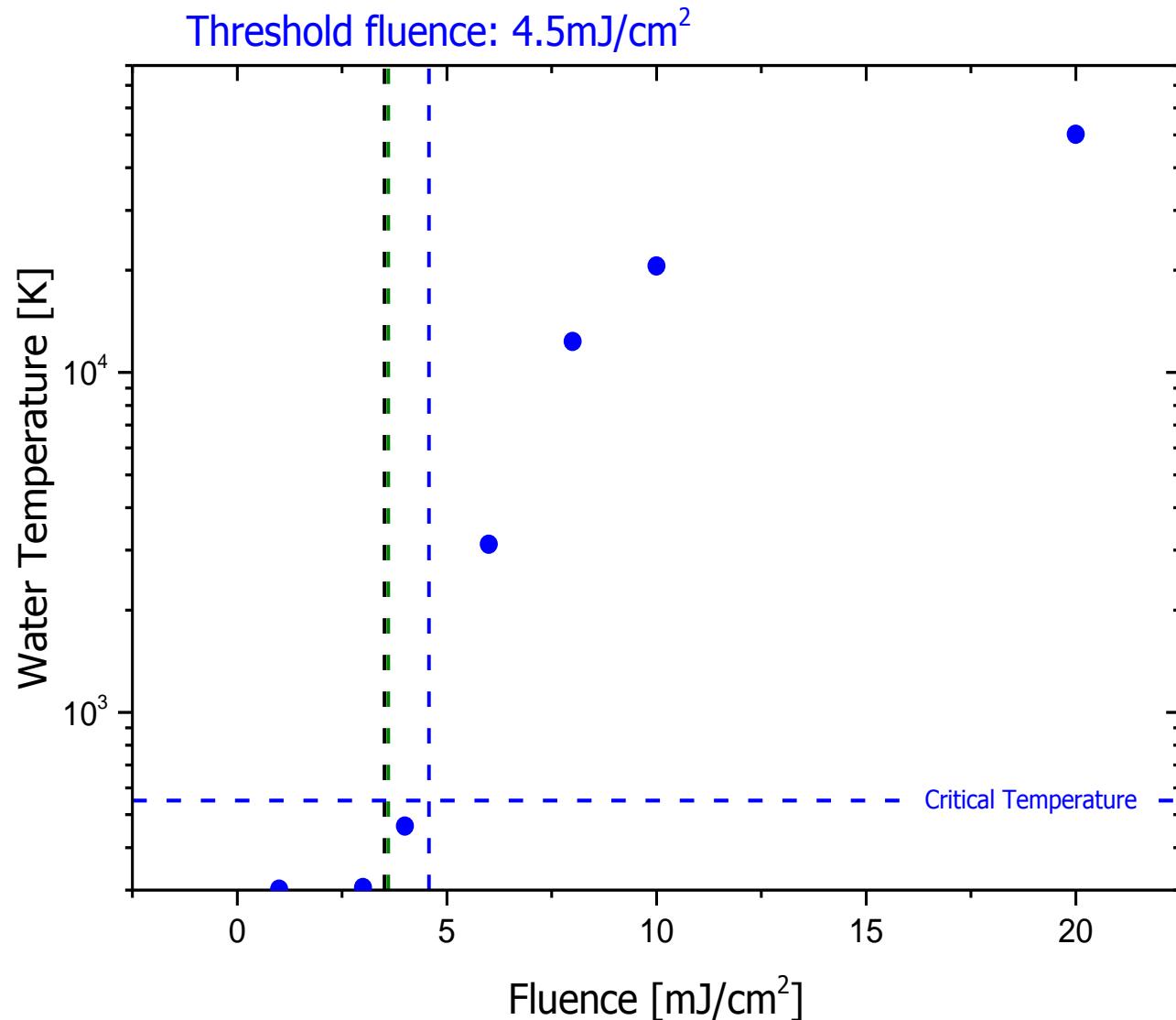
# Plasma Formation



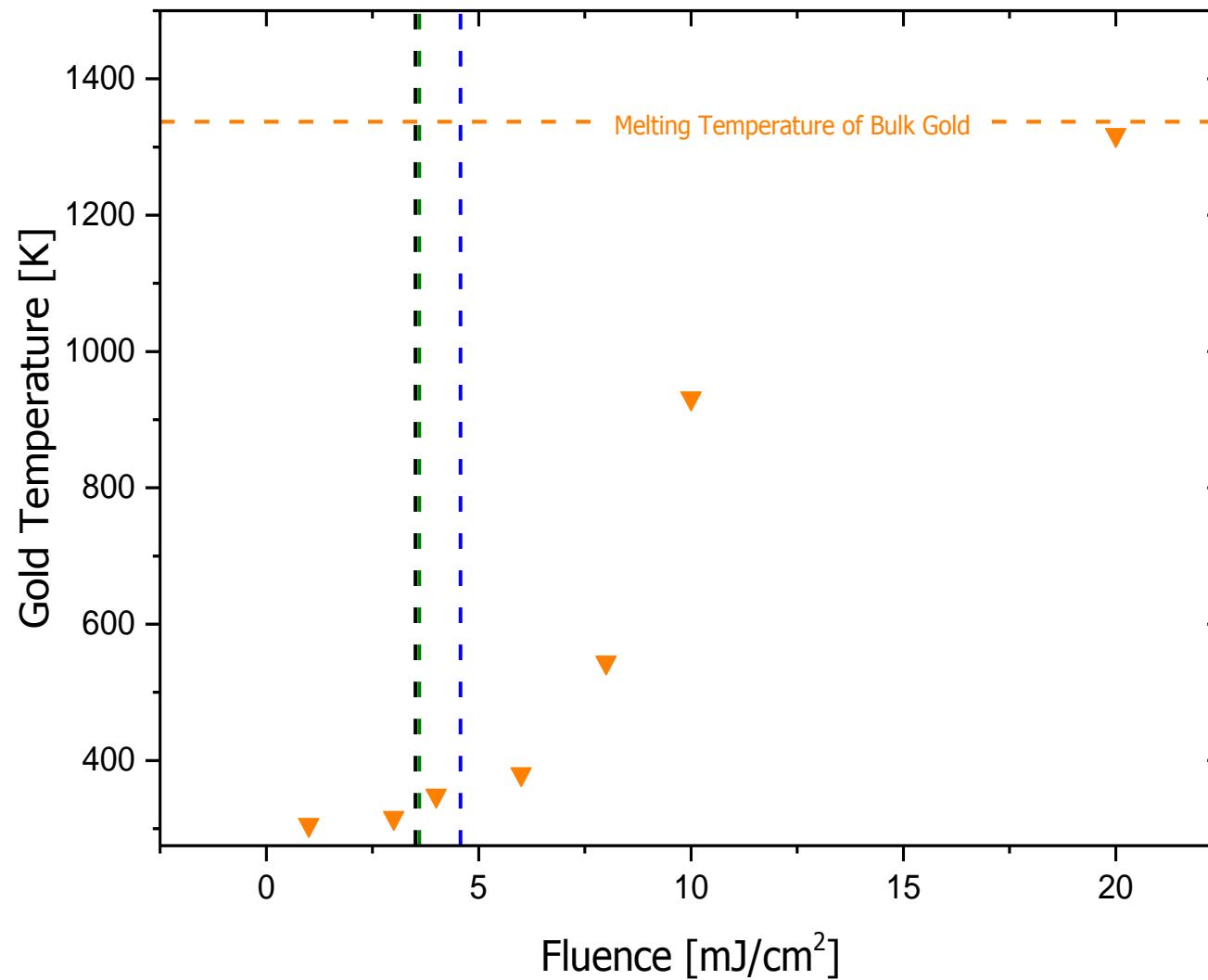
# Plasma Formation



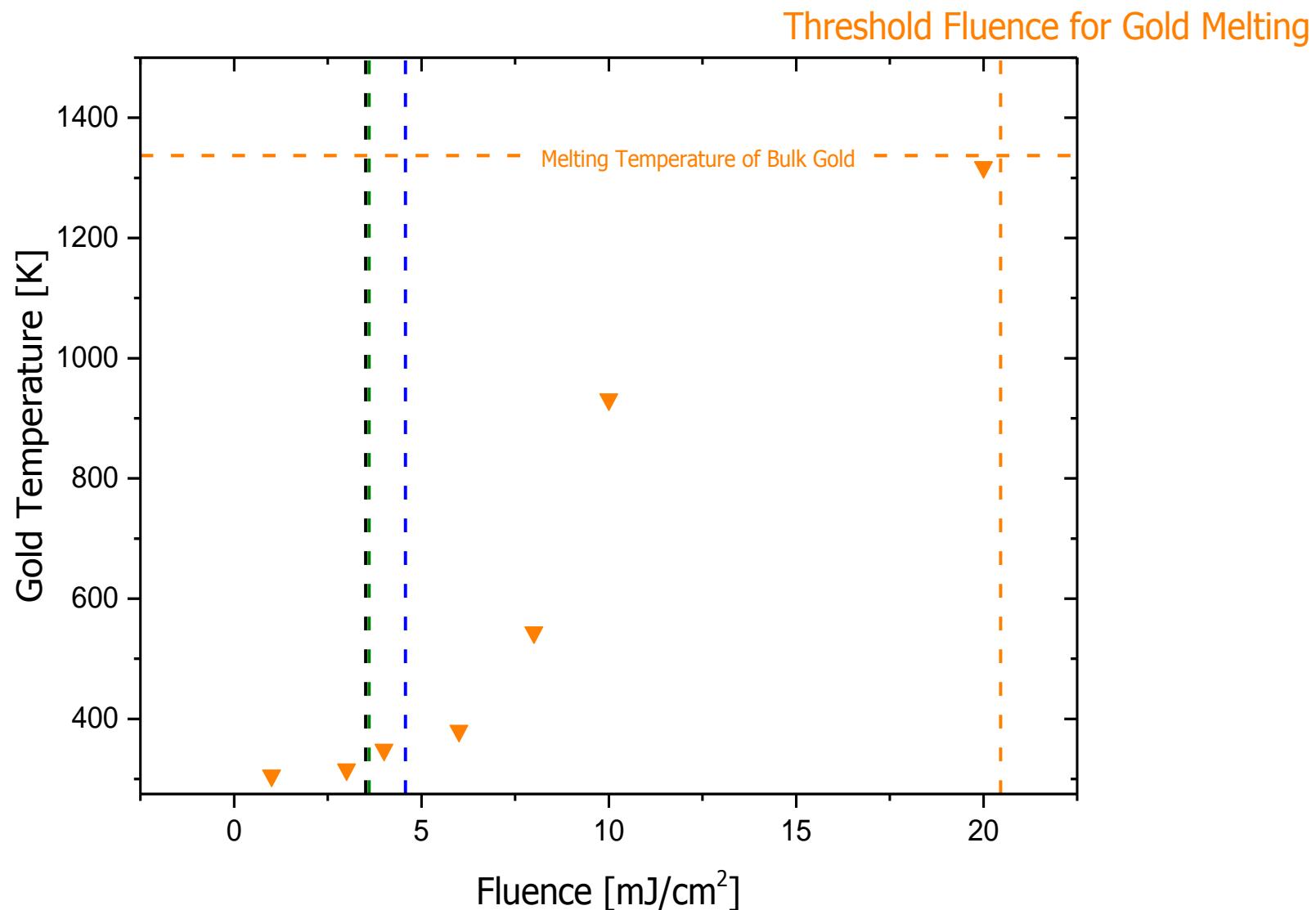
# Plasma Formation



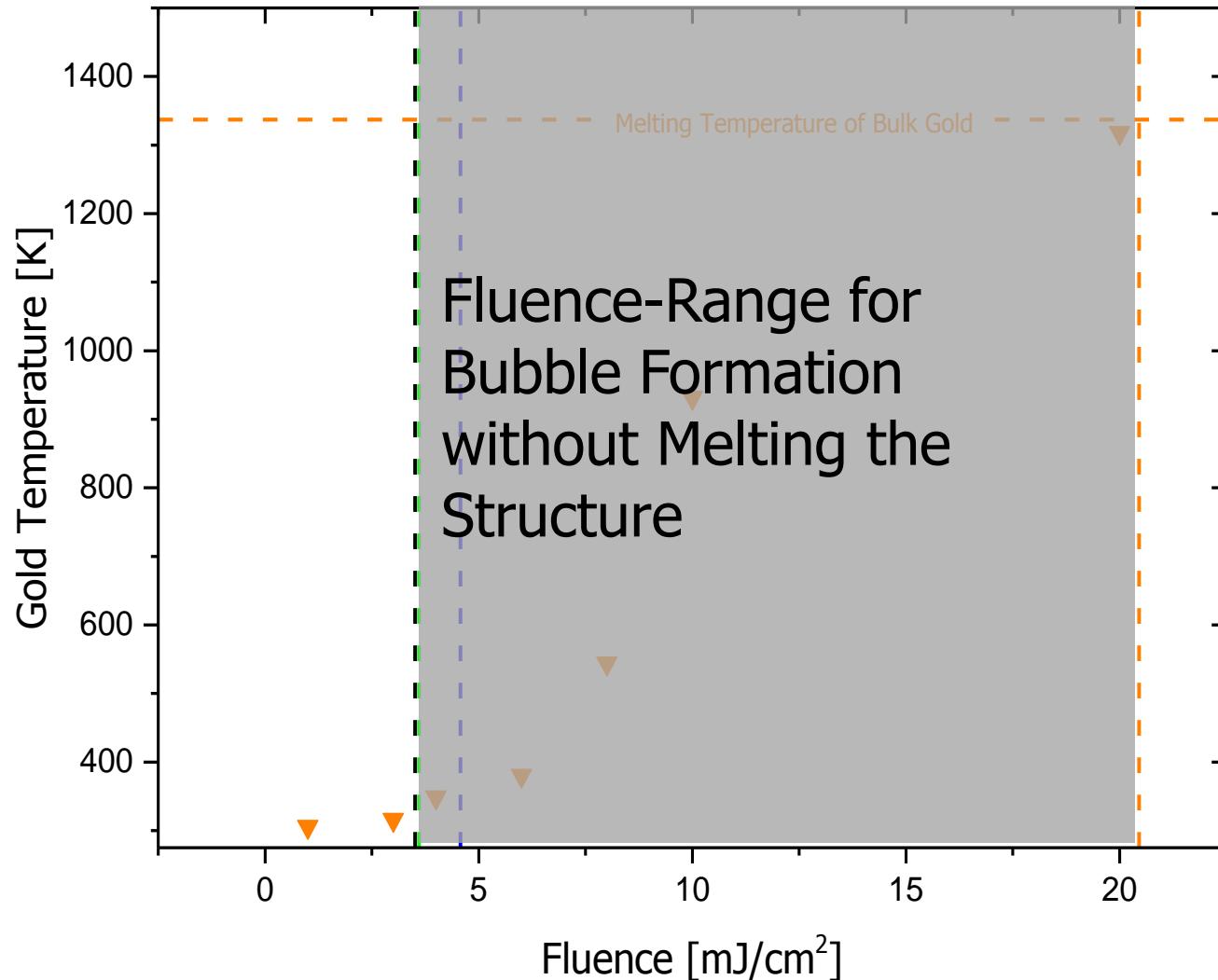
# Plasma Formation



# Plasma Formation



# Plasma Formation



# Design Aspects

- 
- 1. Easy to Fabricate/Large-Scale-Fabrication**
  - 2. Adjustable**
  - 3. Strong Plasmonic Effect for Efficient and Localized Poration**
  - 4. Robust/Stable (Theoretical)**

# Acknowledgements

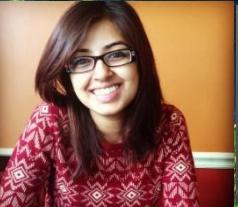


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Vulis



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Saklayen



Marinna  
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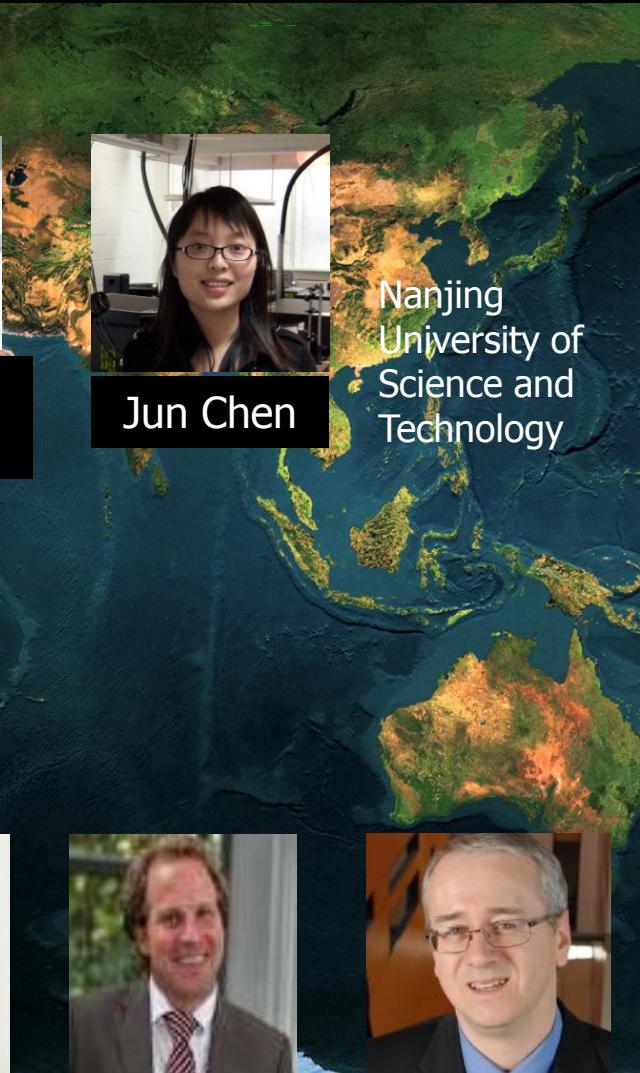
Sébastien  
Courvoisier



Jun Chen



University  
of Geneva



Nanjing  
University of  
Science and  
Technology



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*MIT*



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